

# INTEGRATED APPROACH FOR HIGH RESOLUTION SURFACE CHARACTERIZATION: COUPLING FOCUSED ION BEAM WITH MICRO AND NANO MECHANICAL TESTS

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**Roma, Italy**

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# ROMA TRE, SOME NUMBERS...



[www.uniroma3.it](http://www.uniroma3.it)

- Founded in 1992
- One of the 4 State University in Rome (9 in total)
- 175.000 m<sup>2</sup>
- More than 40.000 students (4.100 enrolled in Engineering)
- More than 700 Researchers and Professors
- Faculty of Engineering:
  - Civil
  - Computer Science
  - Electronic
  - **Mechanical**
    - *Materials Science and Technology research group (STM Group)*

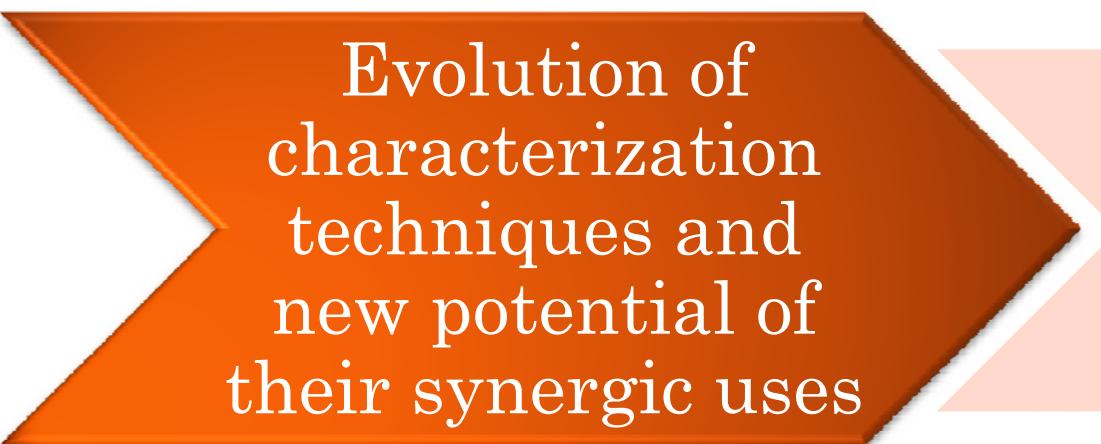
# EVERGREEN NEEDS

*Functional and structural behavior are strongly influenced by micro-structural effects (grain size, defects, precipitates, interfaces, porosity,...)*

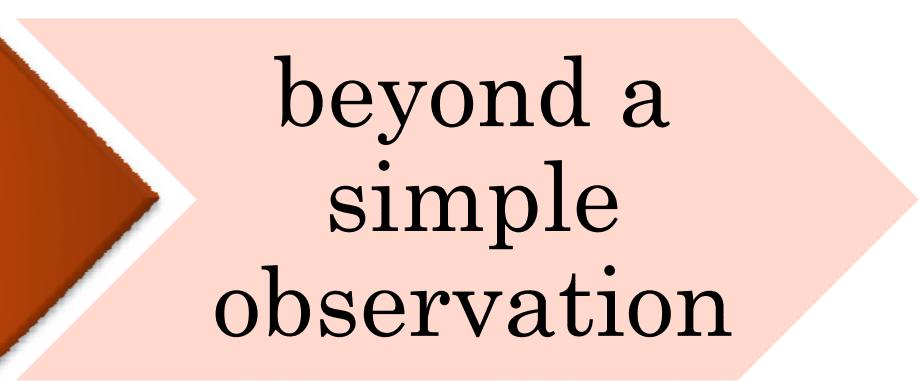
- Ok, not really a news; however...
- **Engineered surfaces** are spreading quickly also in non high-tech products (also in mass products);
- Industrial application of surface modification and coating techniques requires **mechanical and functional characterization** of:
  - Nano-structured materials and coatings
  - Nano-systems
  - Nano-structures
- **Multi-scale** characterization (quick and cheap) procedures are therefore strongly needed for a plethora of needs in:
  - Development
  - Production
  - Maintenance and survey

# INCIPIT

- Conventional characterisation techniques are not completely exhaustive for describing all micro-structural aspects which necessarily determine the actual behaviour of nano-structured materials and coatings
- New developed procedures should also be compatible for in-line quality control processes, or at least cost-saving with respect to traditional high resolution characterisation techniques.
- Needs of standards and standardization procedures



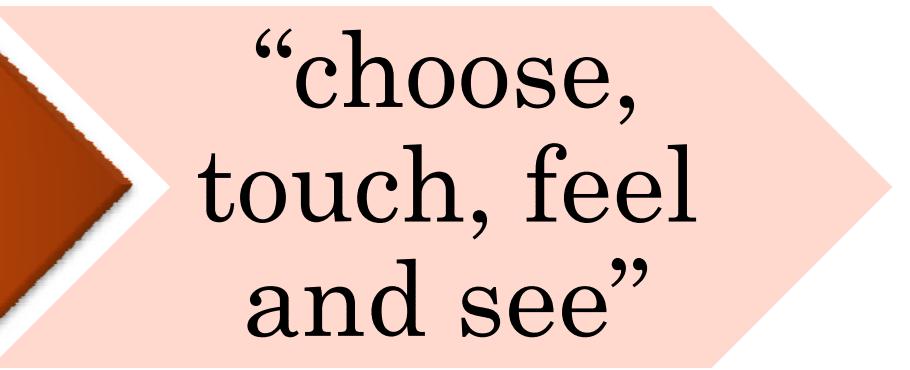
Evolution of  
characterization  
techniques and  
new potential of  
their synergic uses



beyond a  
simple  
observation



Evolution of  
characterization  
techniques and  
new potential of  
their synergic uses



“choose,  
touch, feel  
and see”

# OUTLINE

## Evolution of two “traditional” techniques

### Visualization and machining at the nanoscale

- Resolution
- Other probes than e<sup>-</sup>
- Not only Imaging, but also Milling and Deposition

### Mechanical tests (nanoindentation)

- Applied forces and displacement measurement
- CSM method

## Examples

I  
Nb coatings for  
superconducting  
cavities

II  
Residual stress  
measurement at the  
micro-scale

# ROMA TRE DUAL BEAM

FEI  
Helios 600  
Nanolab

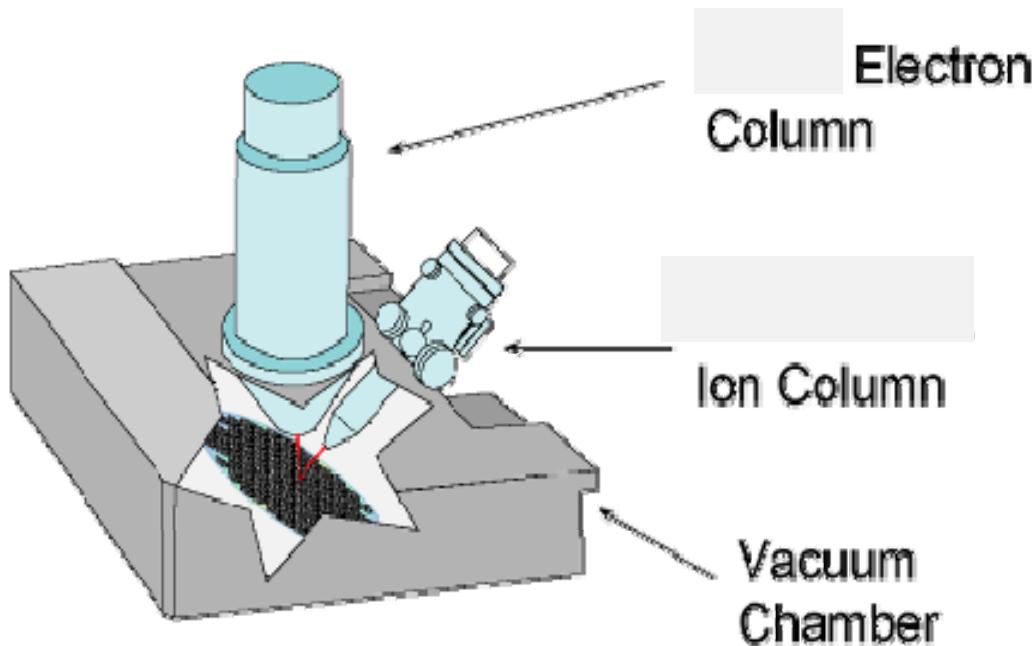
Detectors:  
SE, SI, TLD  
(SE+BSE), STEM.

TEM lamellae  
preparation  
system  
(Omniprobe)

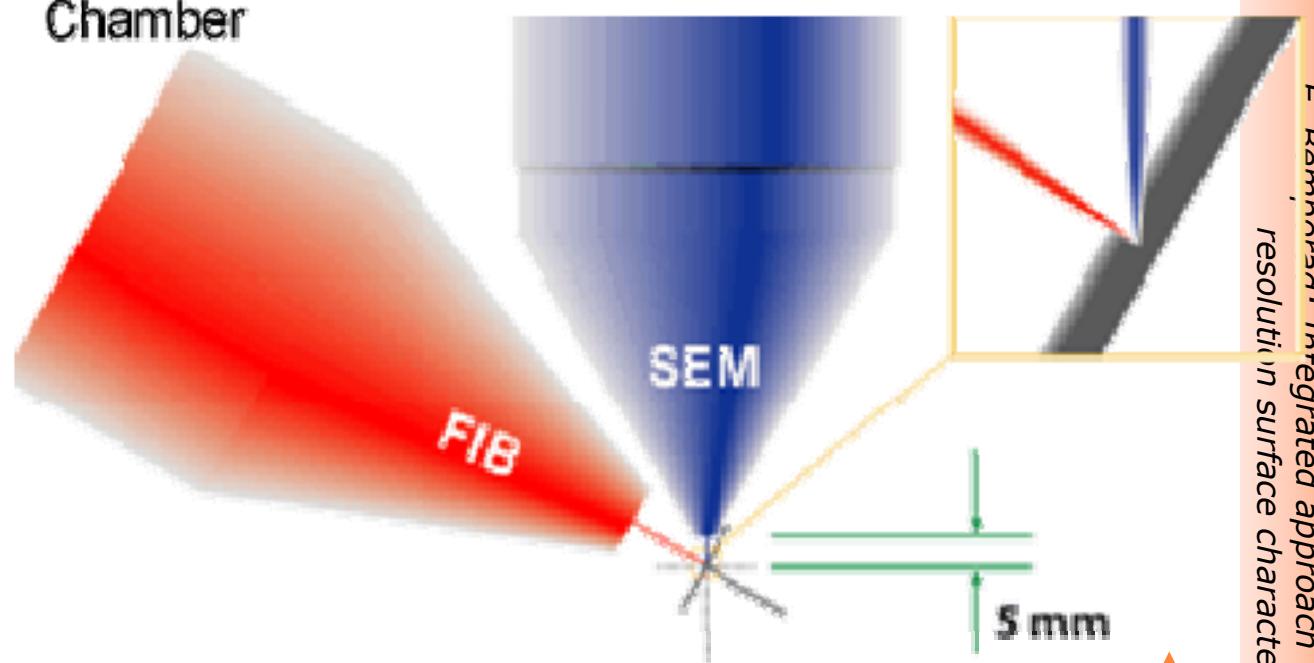
EDS system



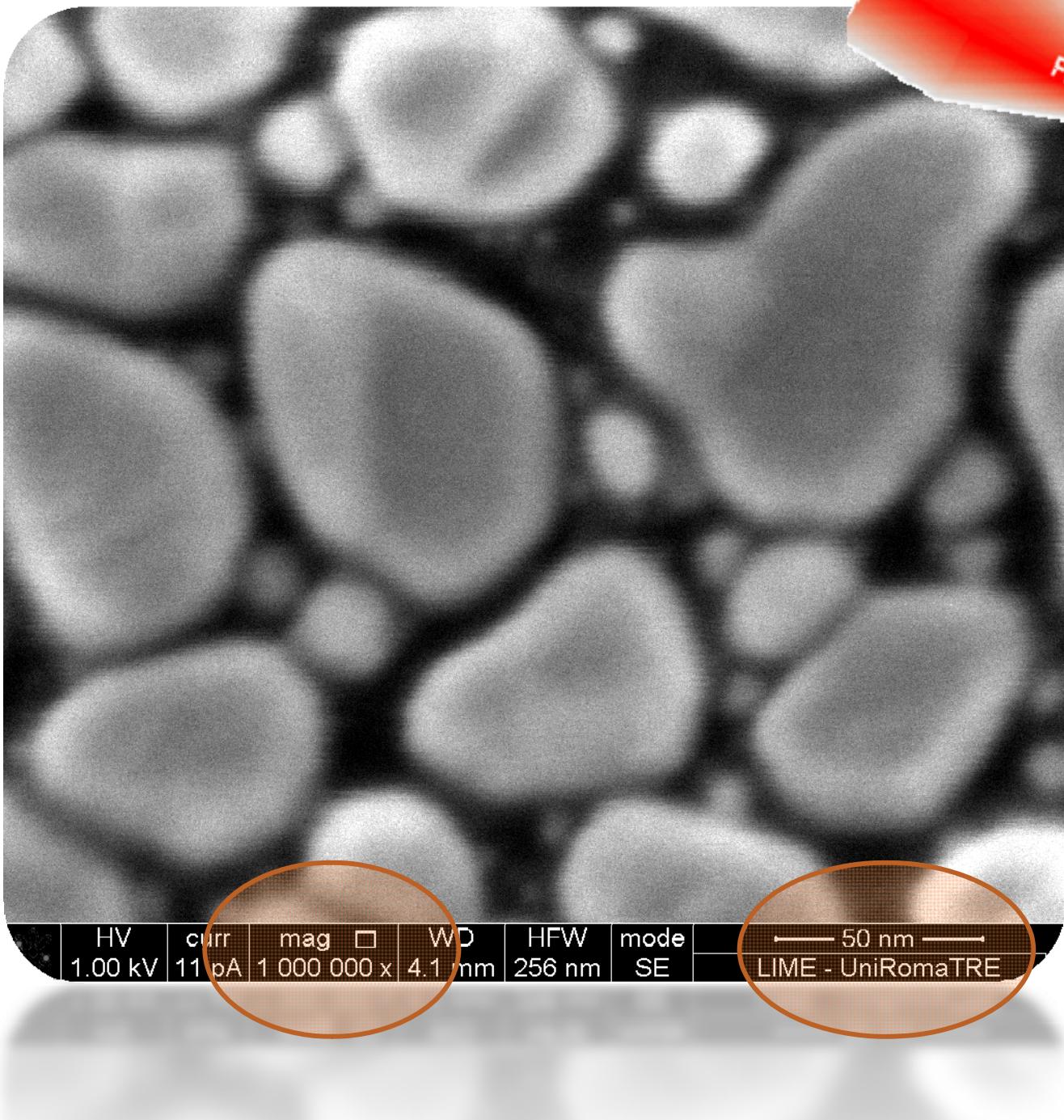
# DUAL BEAM MICROSCOPY (FIB-SEM)



**SEM Column: 0,76 nm @ 15 kV**  
**FIB Column: 5 nm @ 30 kV**  
(spatial resolution)

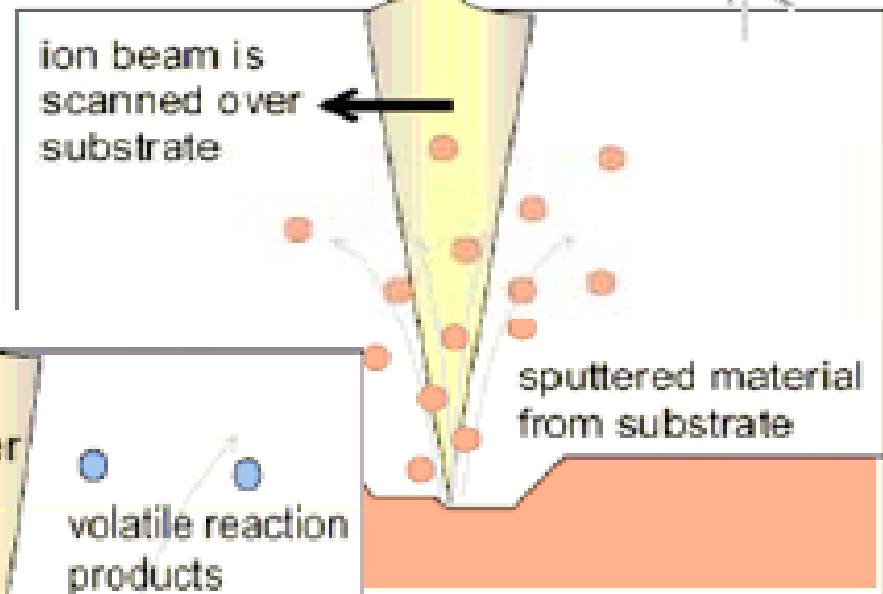
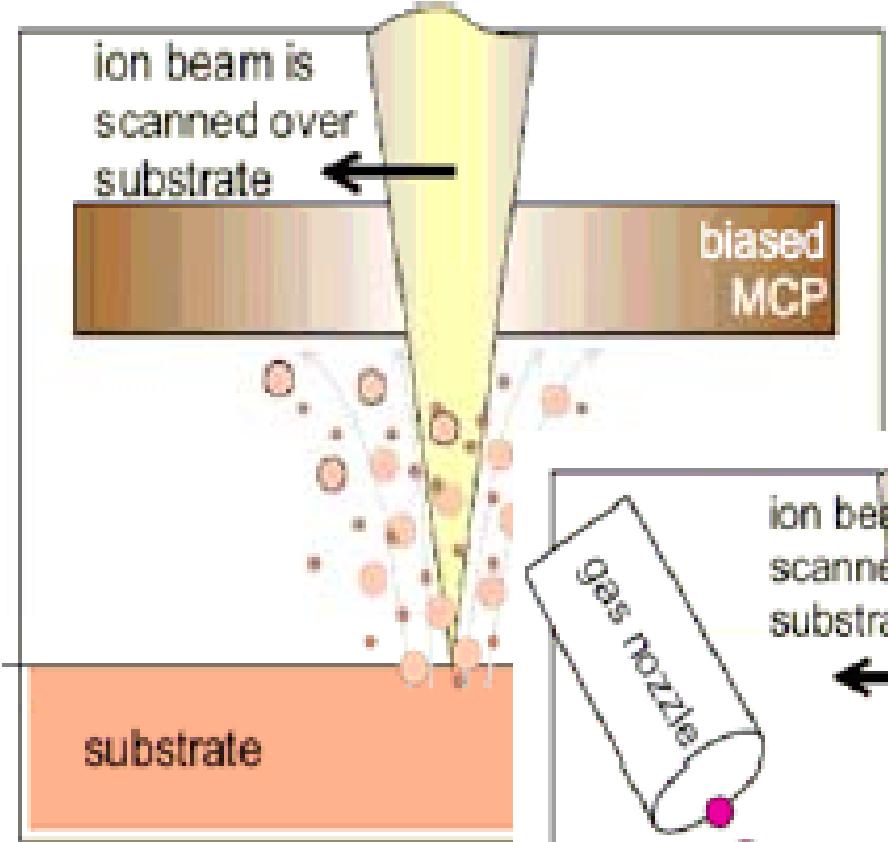


# HIGH RESOLUTION SEM:



# PRINCIPAL FIB MODES

## Imaging:

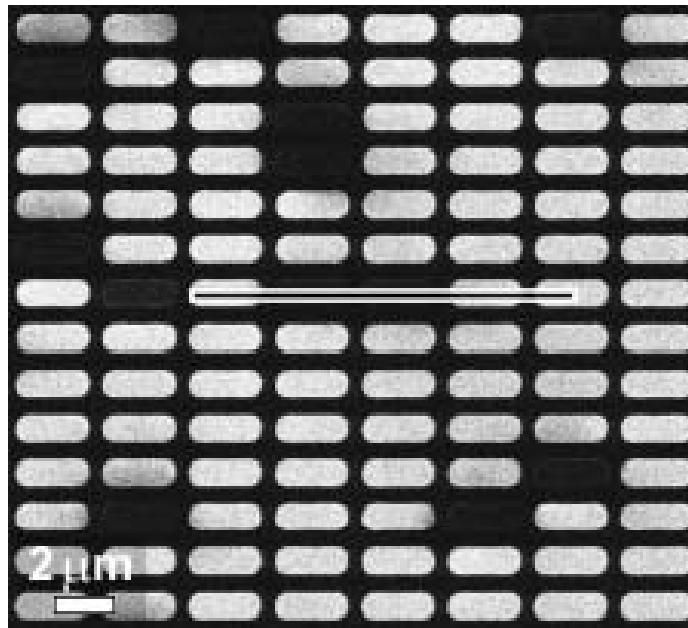
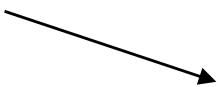


## Milling:

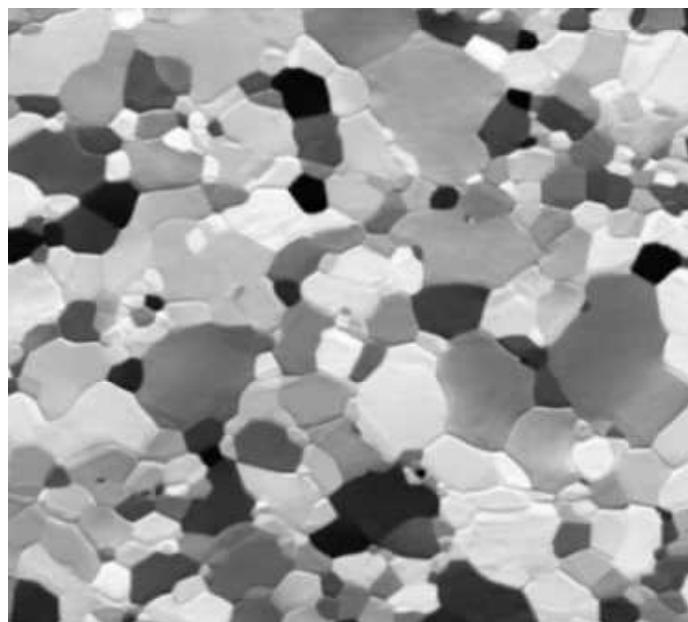
## Deposition:

# FIB MODES: ION IMAGING

- Voltage contrast: insulators appear dark while grounded conductors are bright.



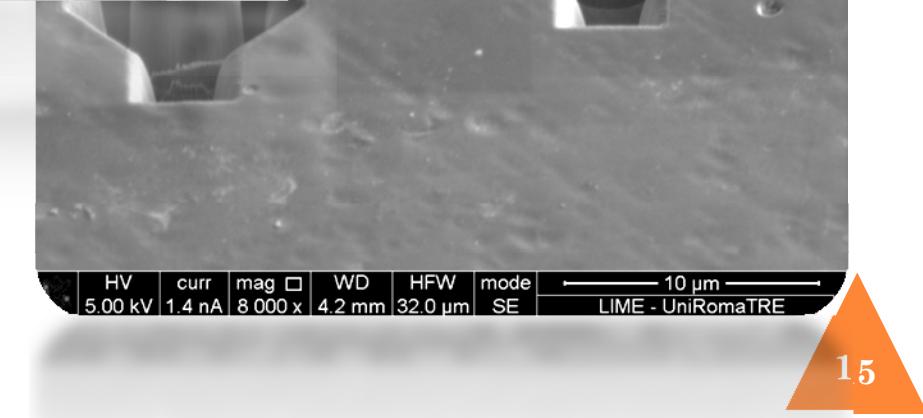
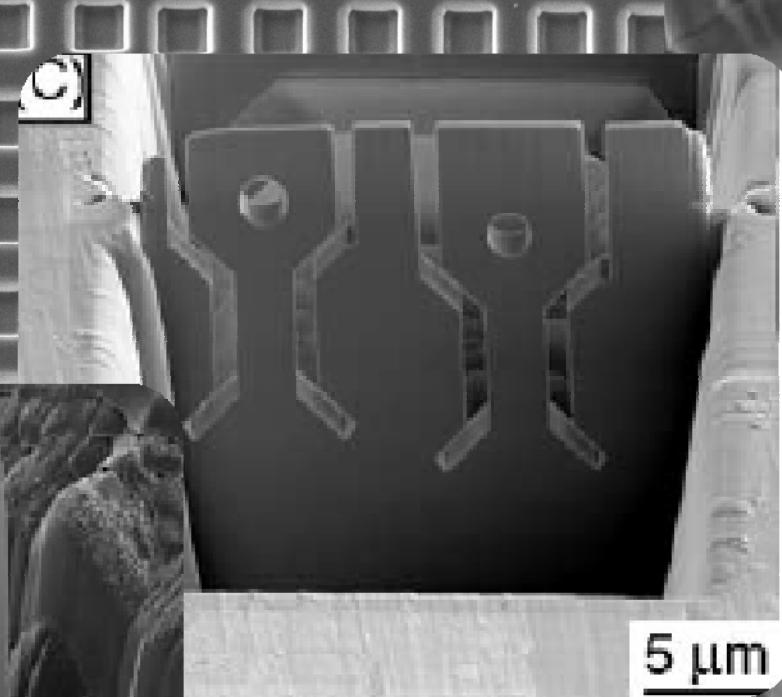
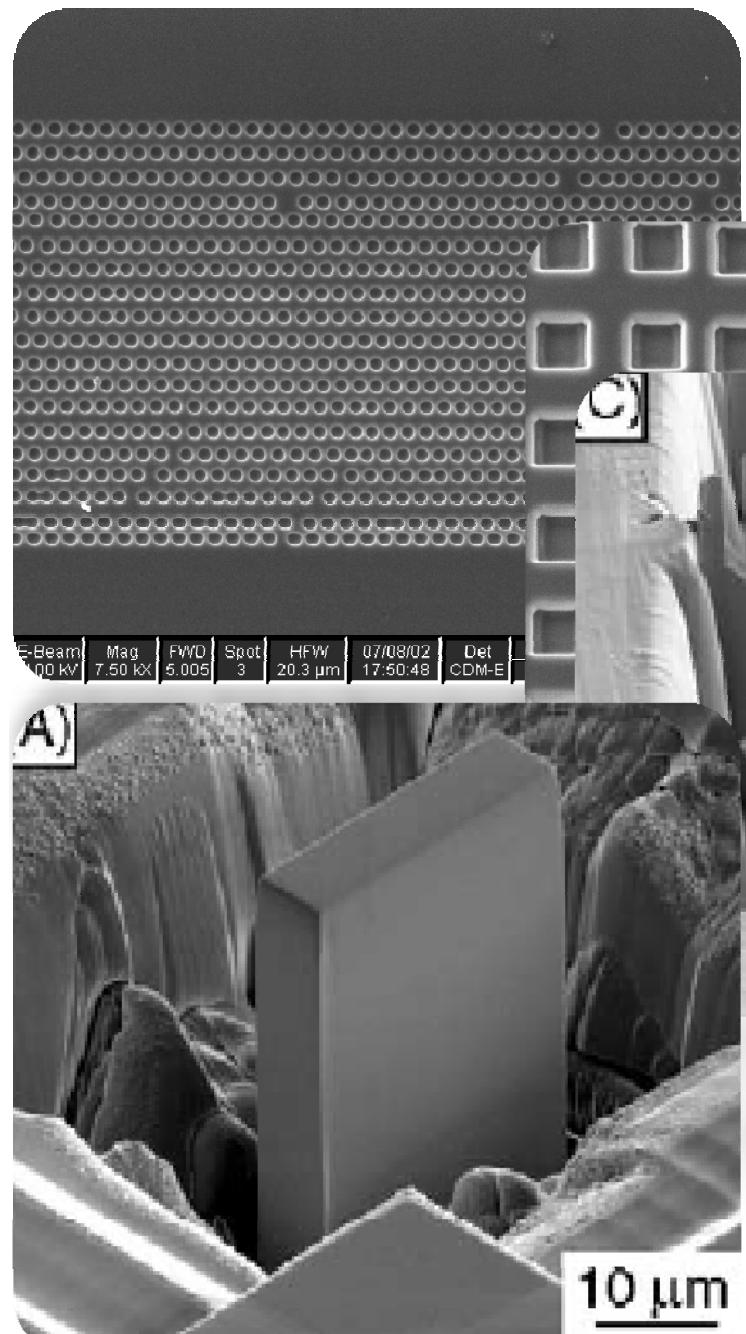
- Materials contrast: differences in yield of secondary particles due to the way energy is lost in the material.



- Crystallographic orientation contrast (channeling contrast): incident ions are channeled down between lattice planes of the specimen.



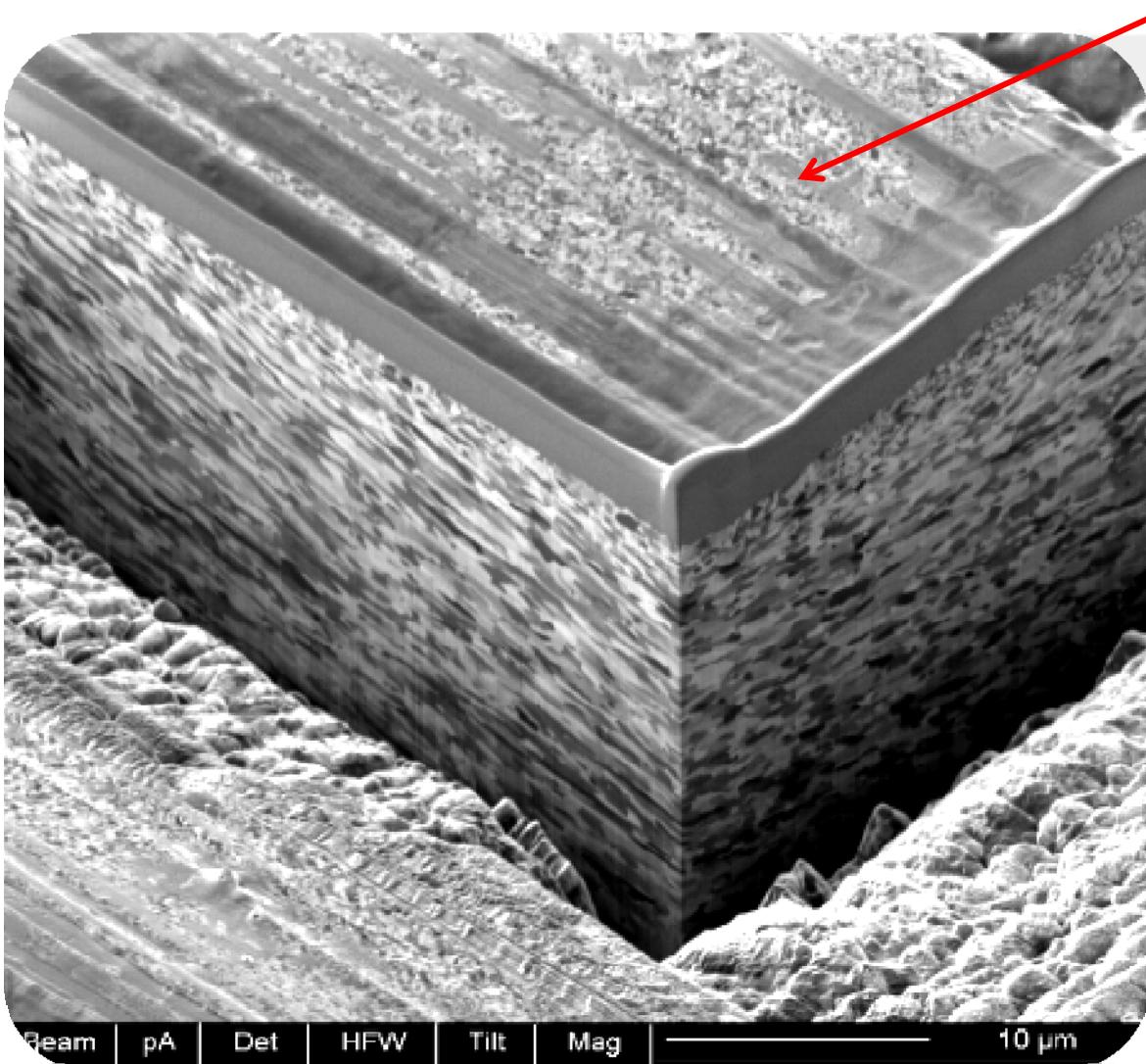
# FIB MODES: ION MILLING



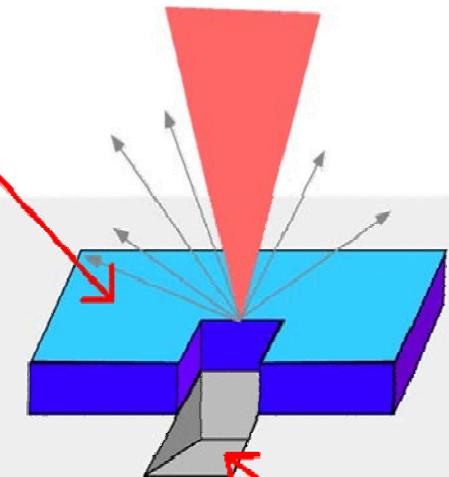
# FIB MODES: DEPOSITION (PT)



# CROSS SECTIONS

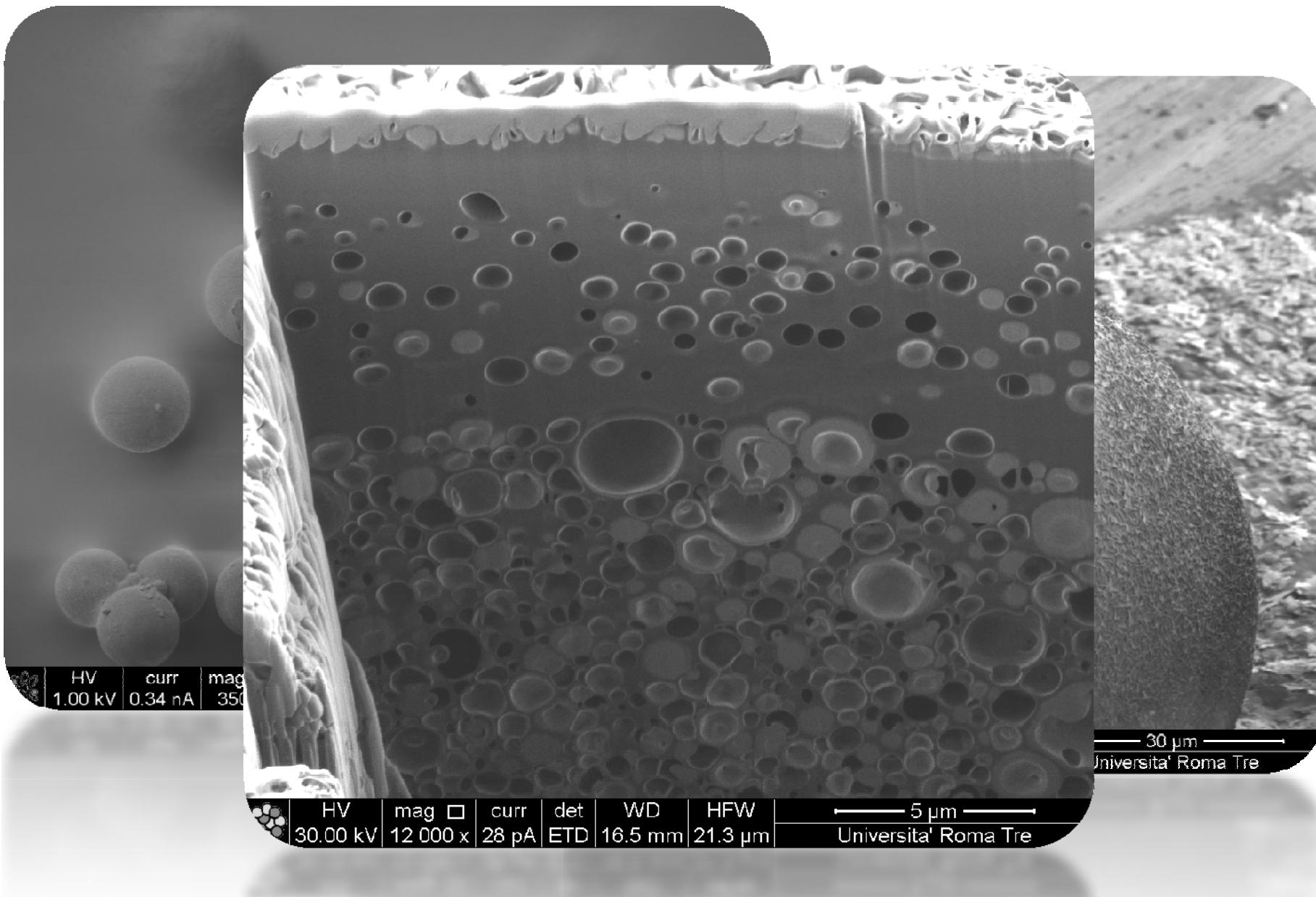


Rastering focused ion beam ( $\text{Ga}^+$ )



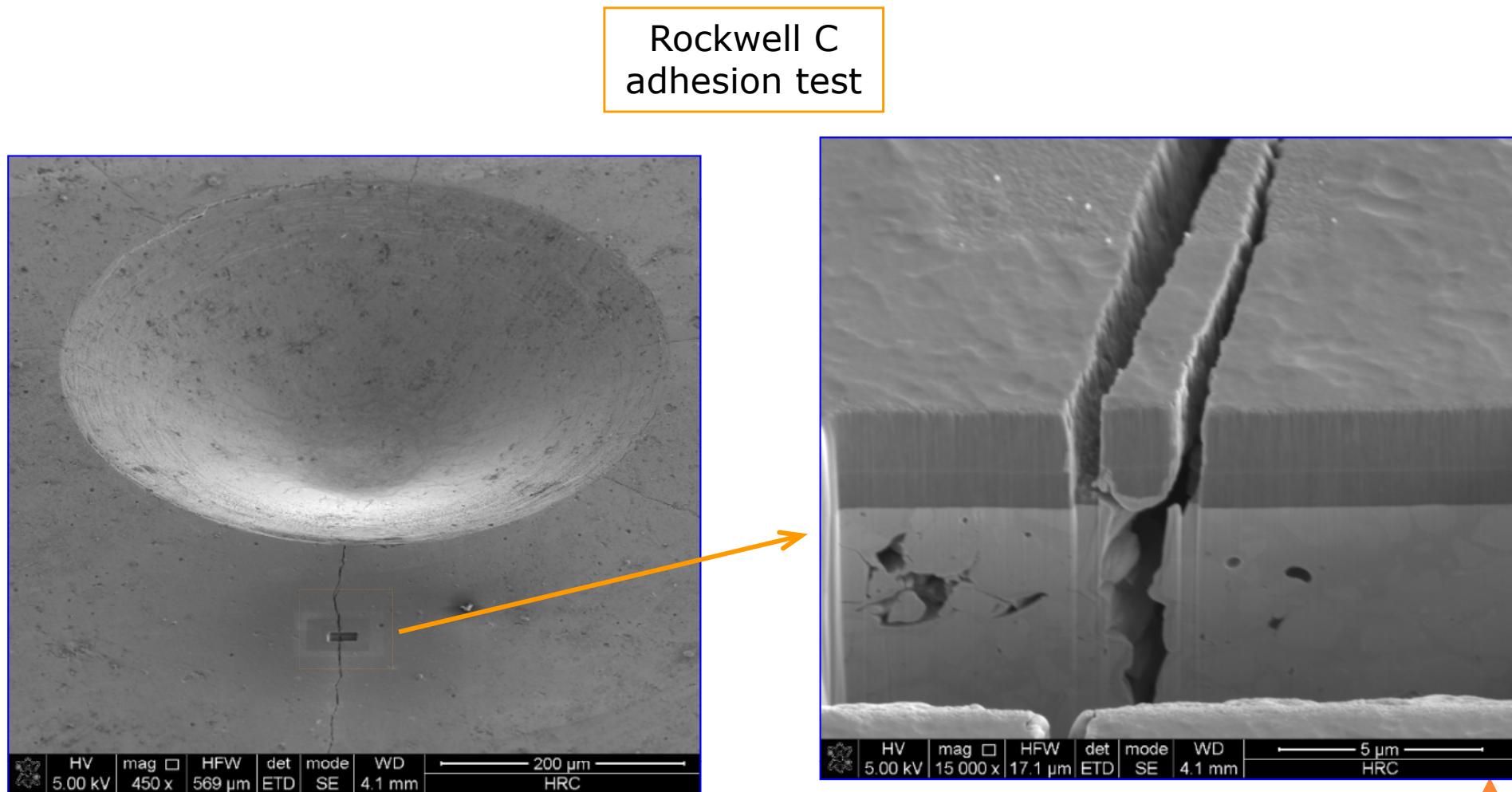
Milled hole

# CHARACTERIZATION WITH DUAL BEAM MICROSCOPY



# CHARACTERIZATION WITH DUAL BEAM MICROSCOPY

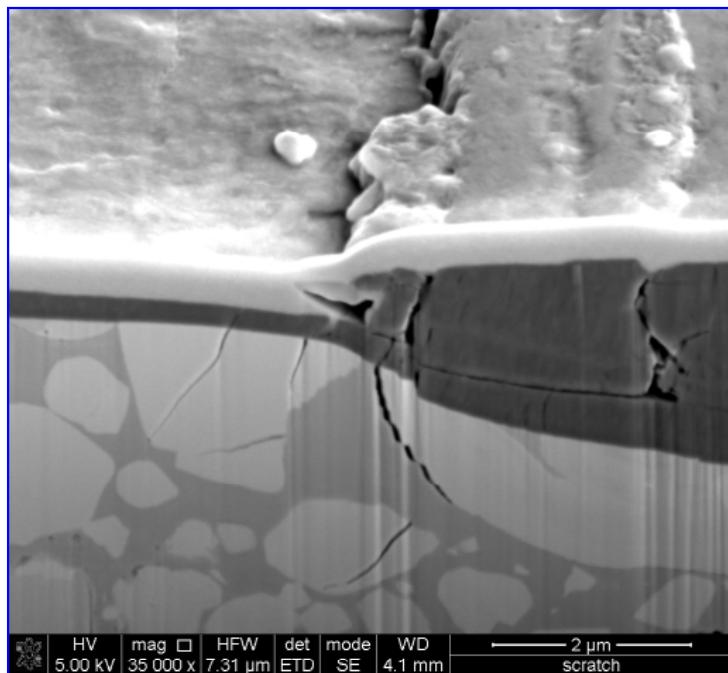
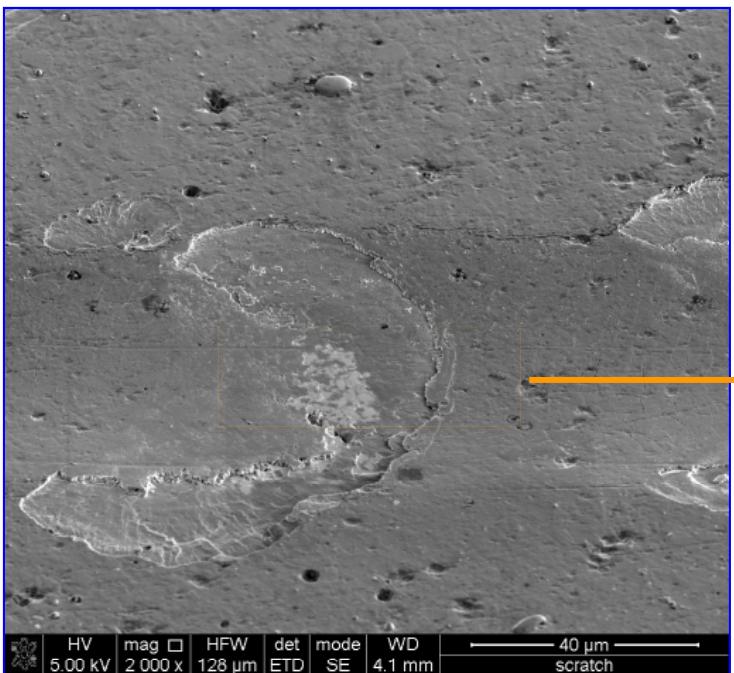
Multiscale and multitechnique approach to mechanical characterization of tribological coatings



# CHARACTERIZATION WITH DUAL BEAM MICROSCOPY

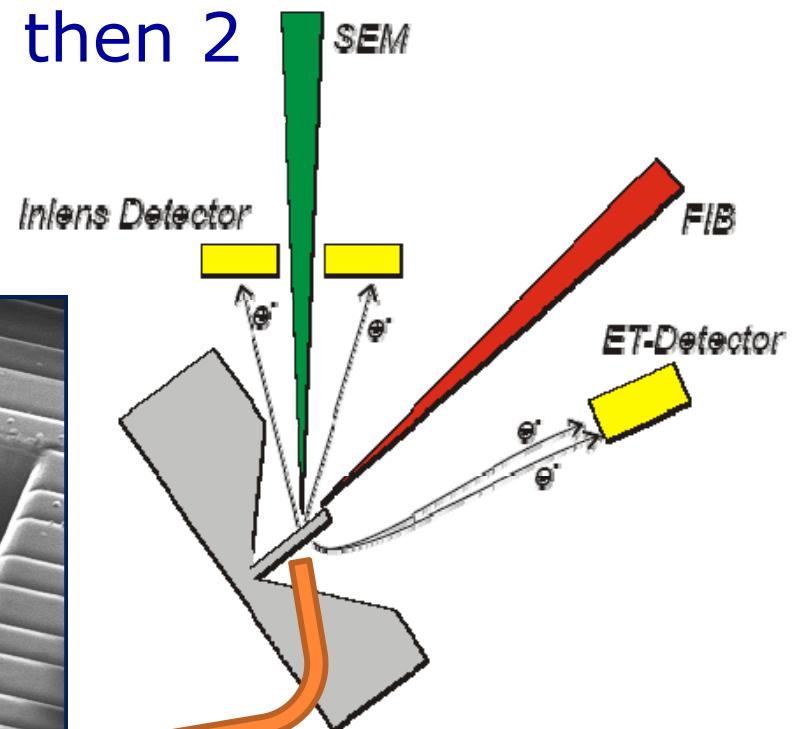
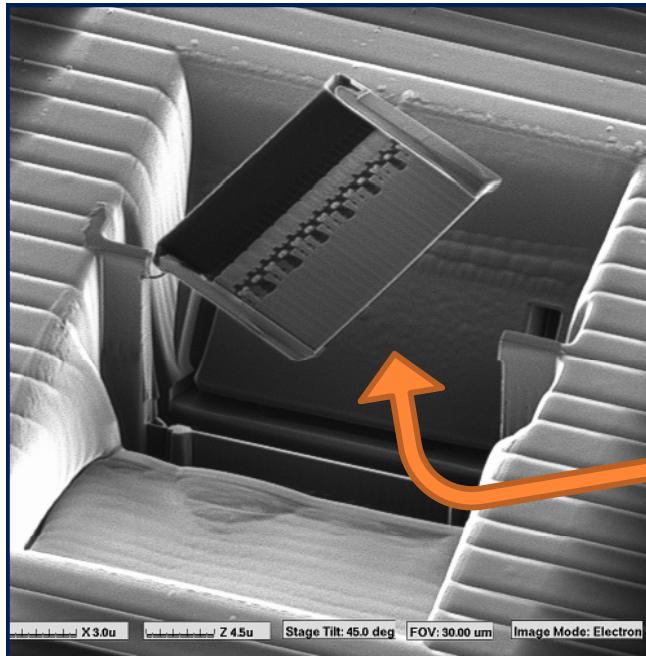
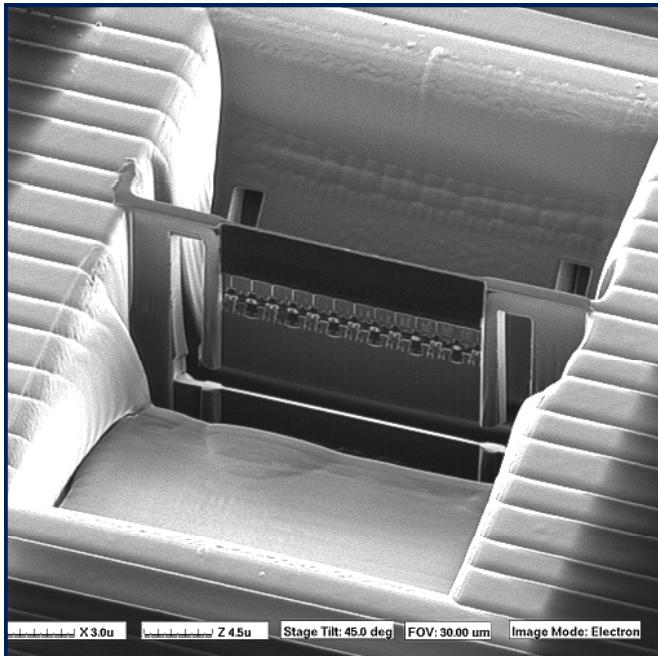
Multiscale and multitechnique approach to mechanical characterization of tribological coatings

Scratch test  
 $L_{c3}$  failure

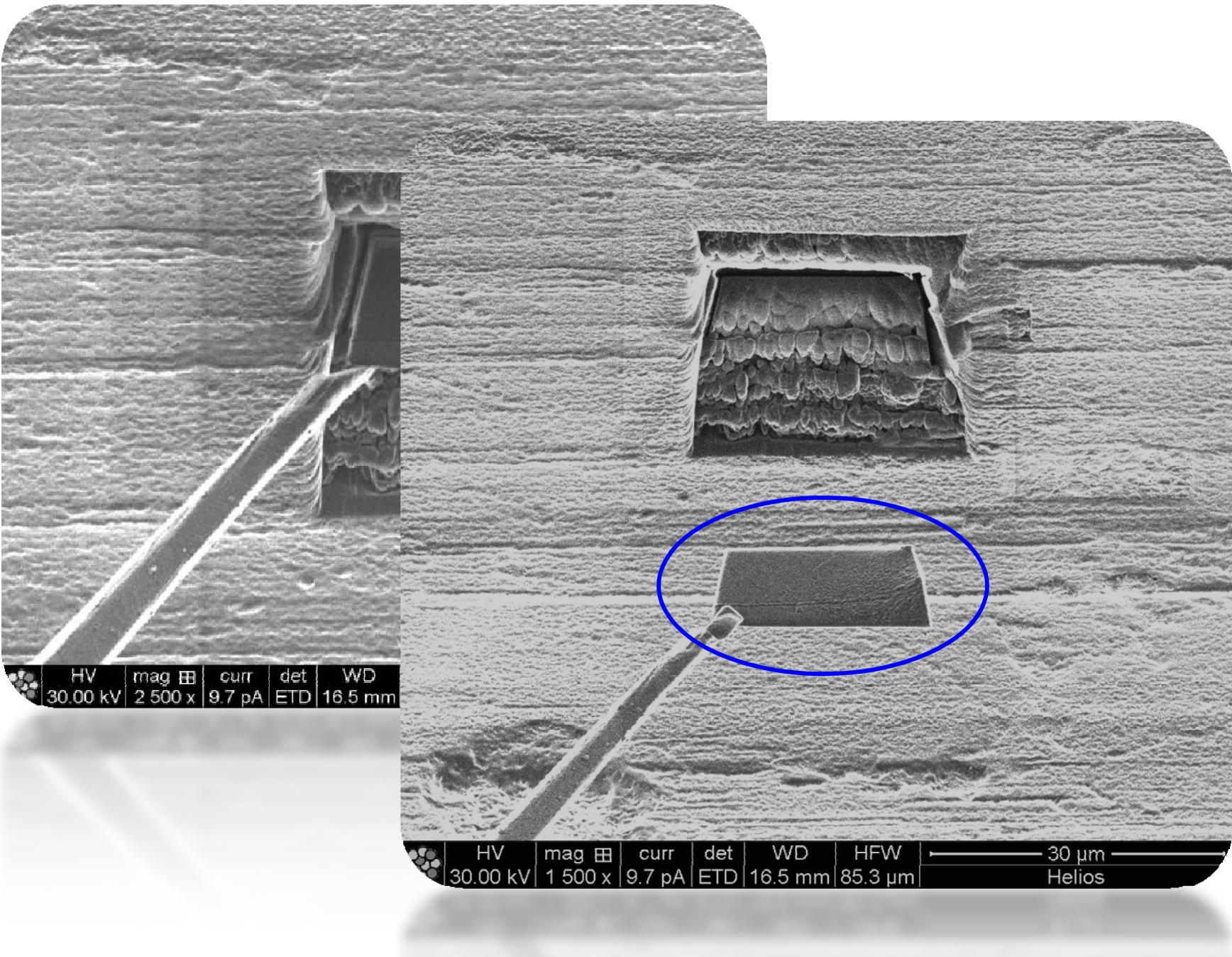


# TEM SAMPLE PREPARATION WITH FIB

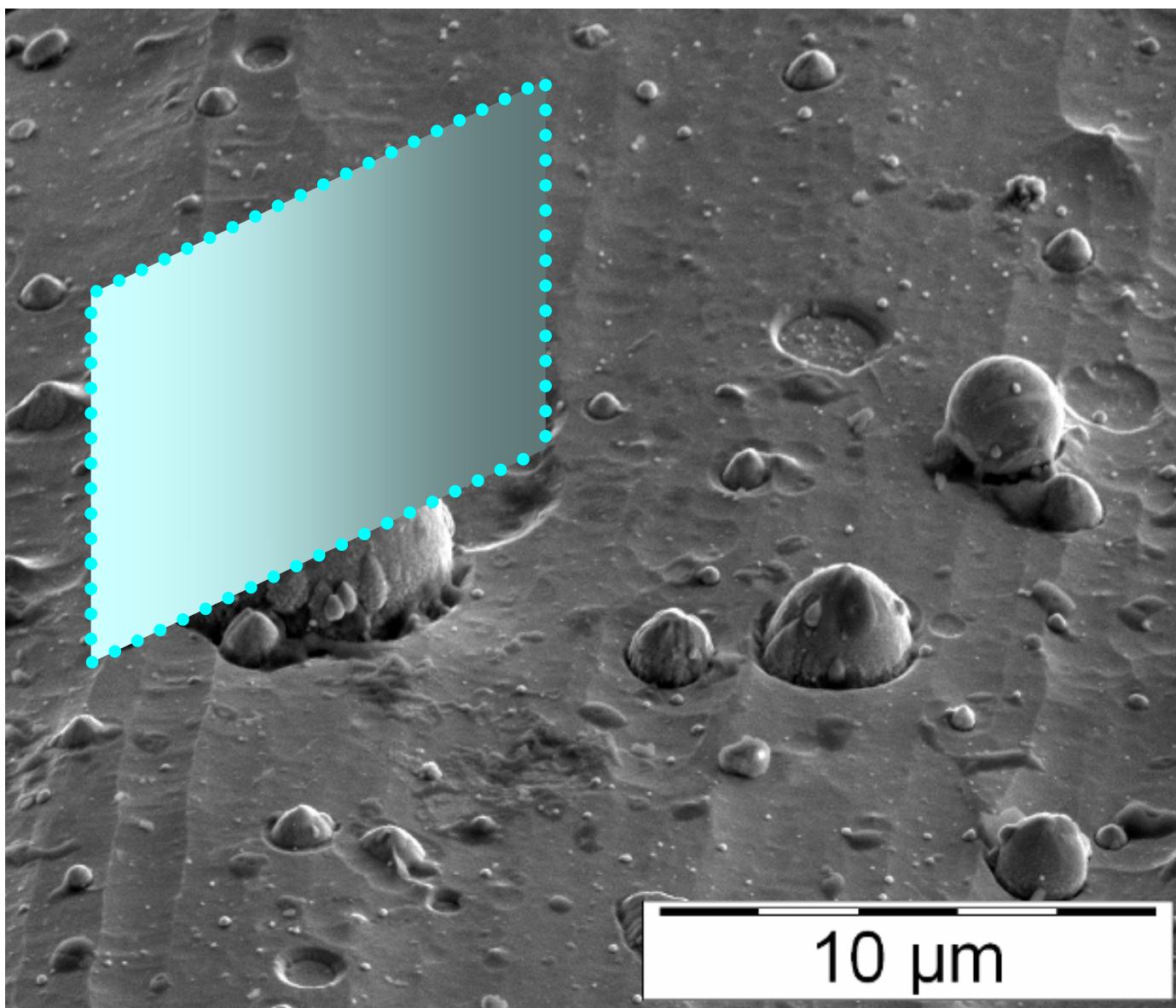
- The sample surface is investigated before cutting to determine the area of interest.
- Then the sample is milled and polished with predefined milling patterns
- Time for a lamella preparation: less than 2 hours with expert operator



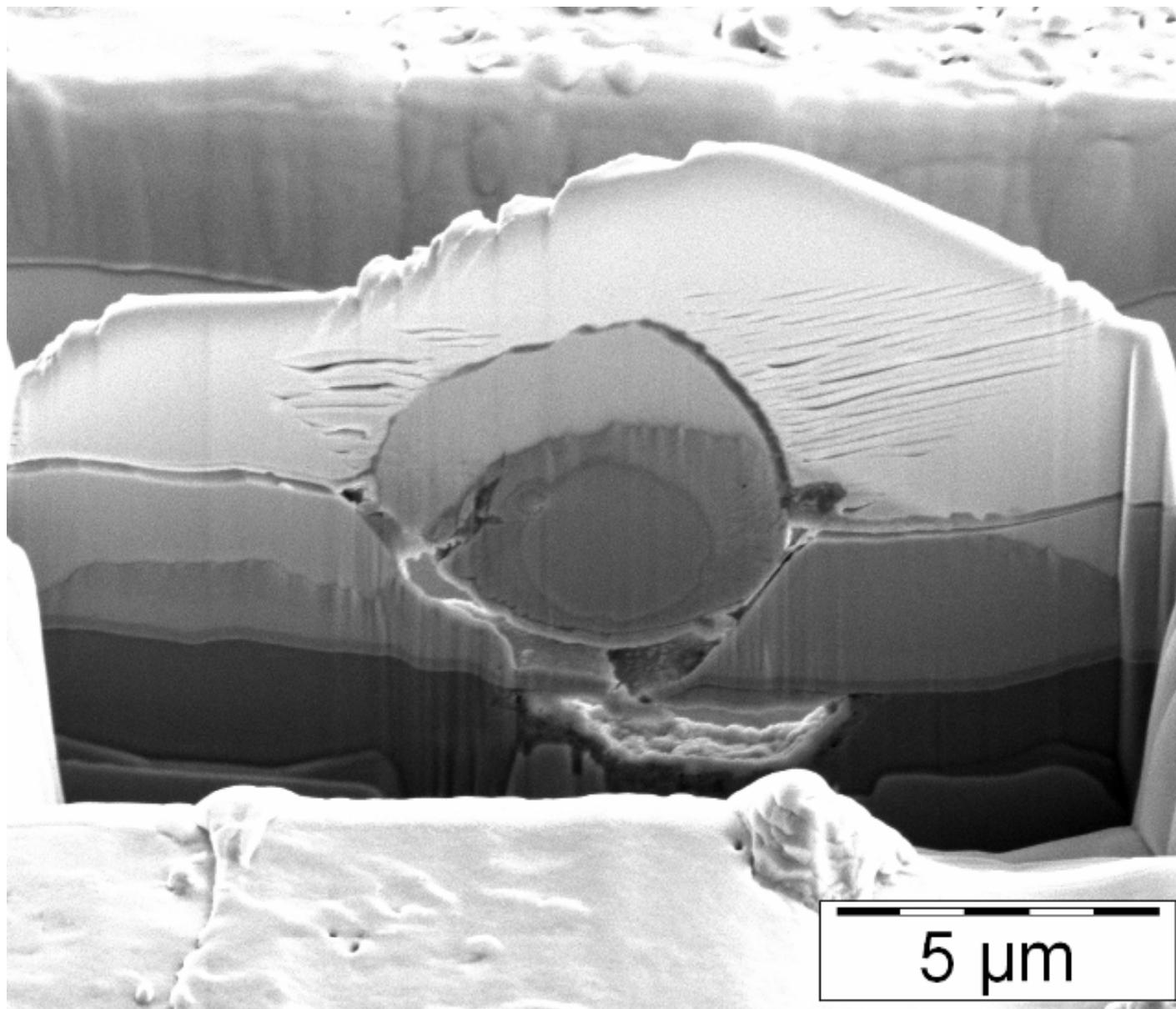
# TEM LAMELLAE EXTRACTION



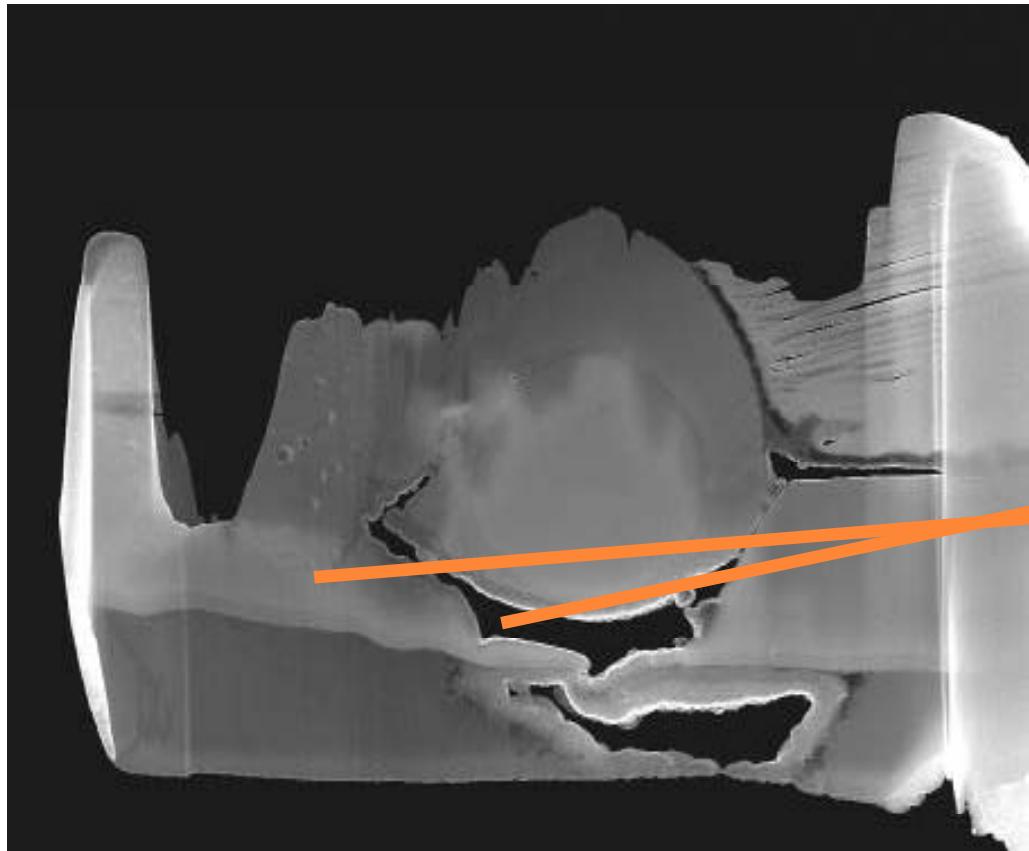
# SITE SPECIFIC TEM X-VIEW



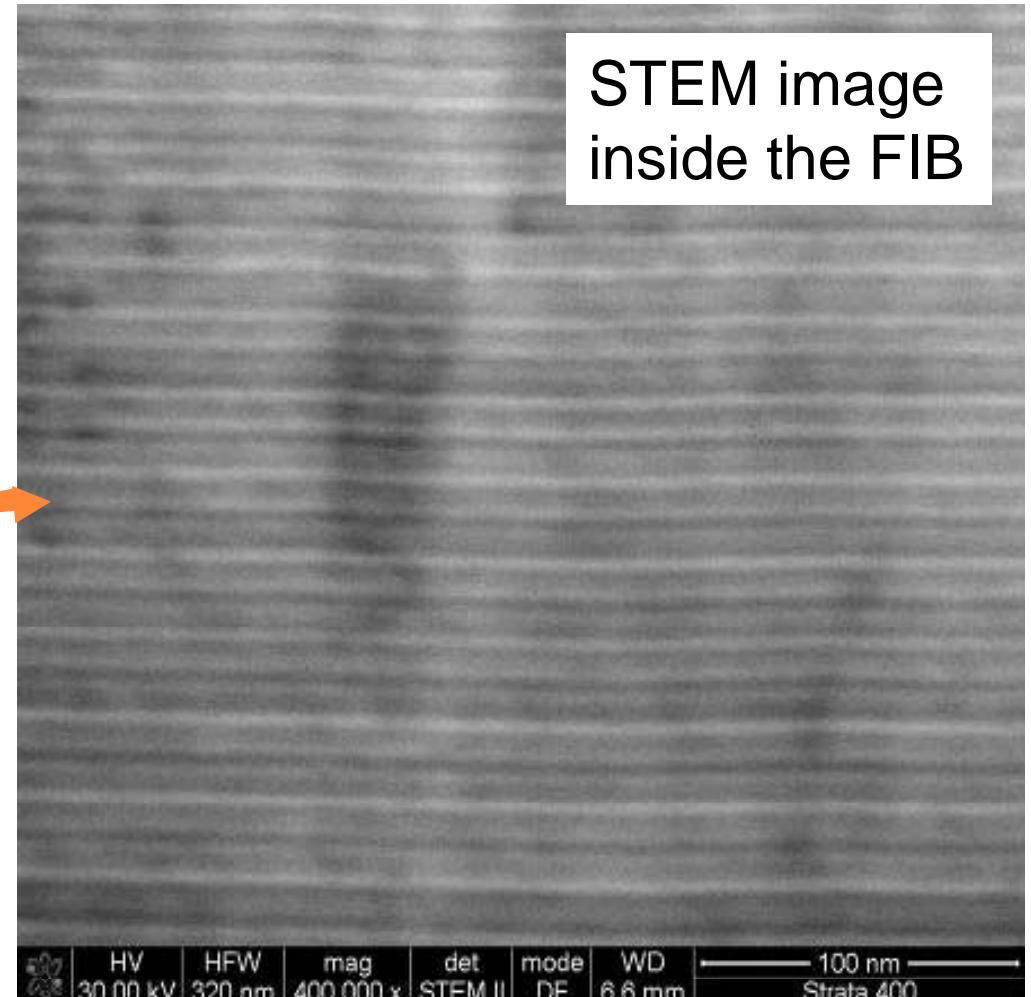
# SITE SPECIFIC TEM X-VIEW



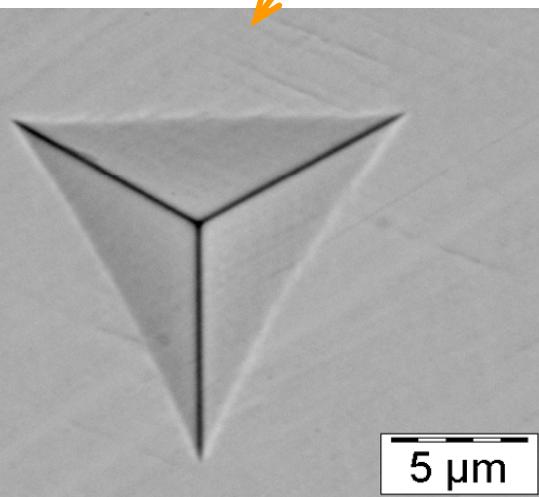
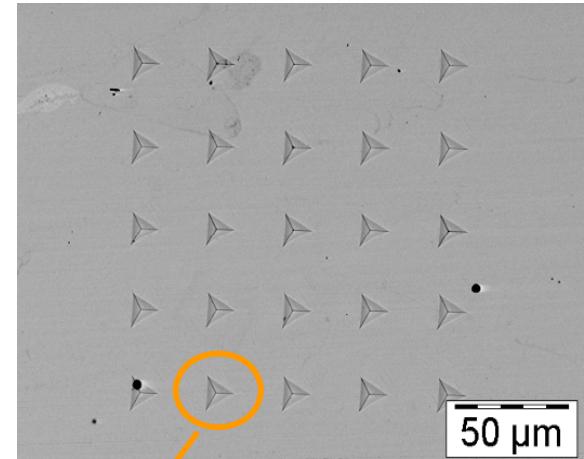
# SITE SPECIFIC TEM X-VIEW



HV | HFW | mag | det | mode | WD | tilt | — 5 μm —  
18.00 kV | 17.1 μm | 15 000 x | TLD | SE | 5.1 mm | -0 °

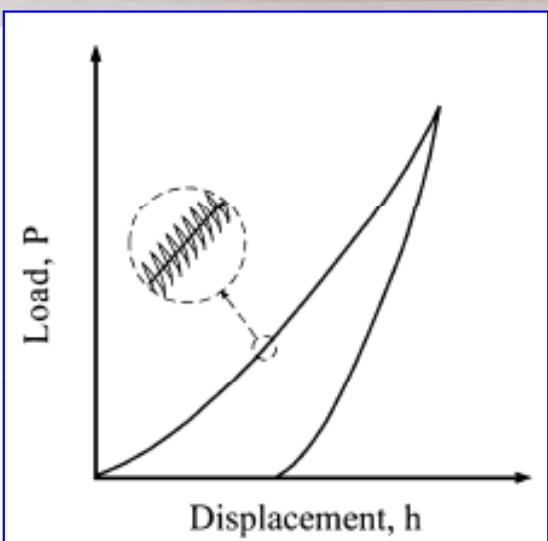


# UNIVERSITY ROMA TRE NANOHARDNESS TESTER



Berkovich tip

# NANO INDENTER



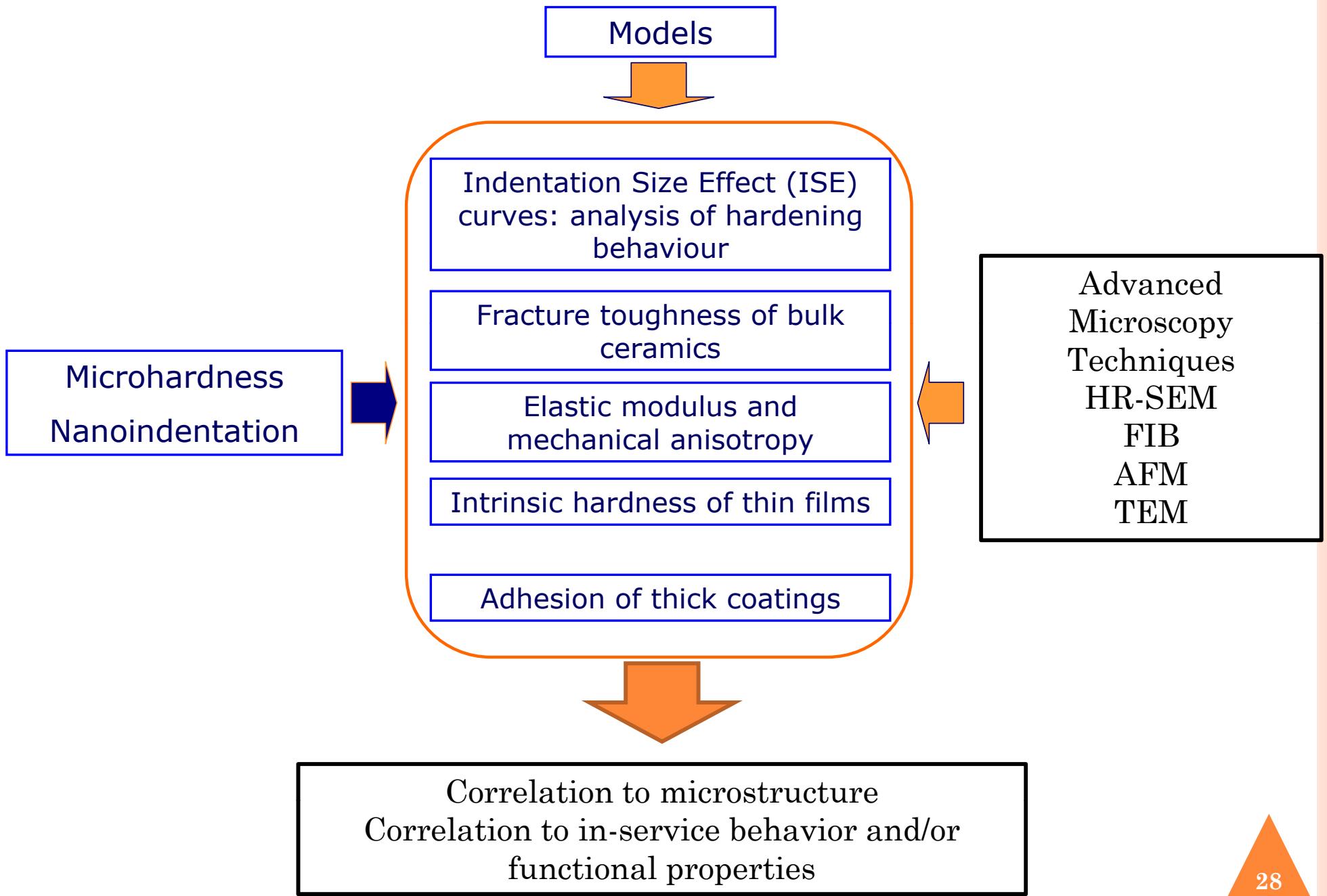
**CSM Method**

## SYSTEM SPECIFICATIONS

### Standard Indentation Head Assembly

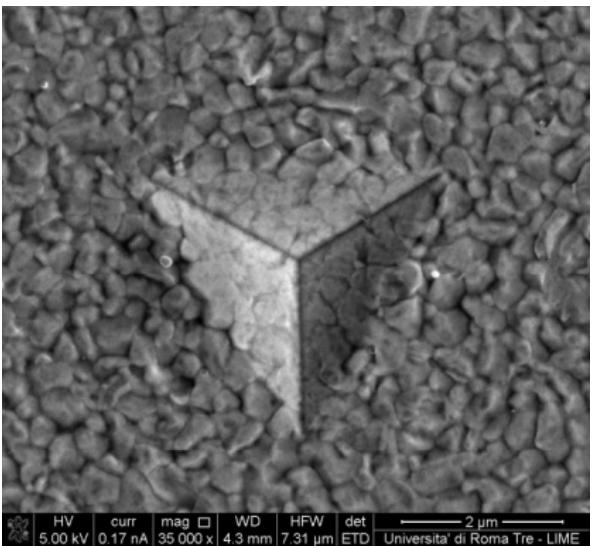
Displacement resolution	<0.01 nm
Total indenter travel	1.5 mm
Maximum indentation depth	>500 µm
Load application	Coil / magnet assembly
Displacement measurement	Capacitance gauge
Loading capability	
Maximum load (standard)	500 mN
Maximum load with DCM option	10 mN
Maximum load with high-load option	10 N
Load resolution	50 nN
Contact force	<1.0 µN
Load frame stiffness	$\approx 5 \times 10^6$ N/m
Indentation placement	
Useable sample area	100 x 100 mm
Position control	automated remote with mouse
Positional accuracy	1 µm

# INTEGRATED CHARACTERIZATION APPROACH



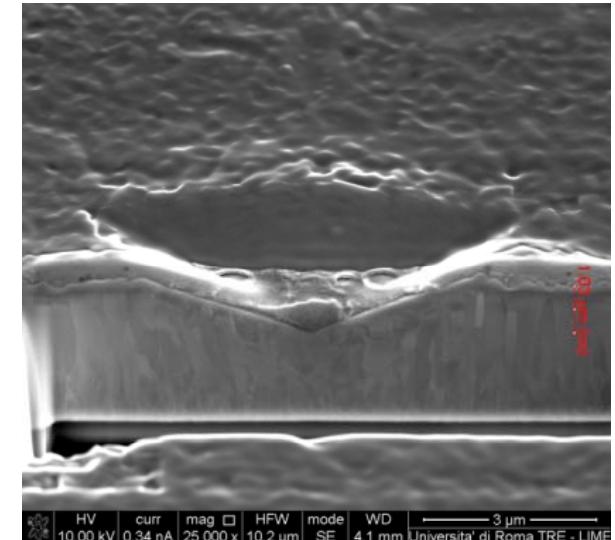
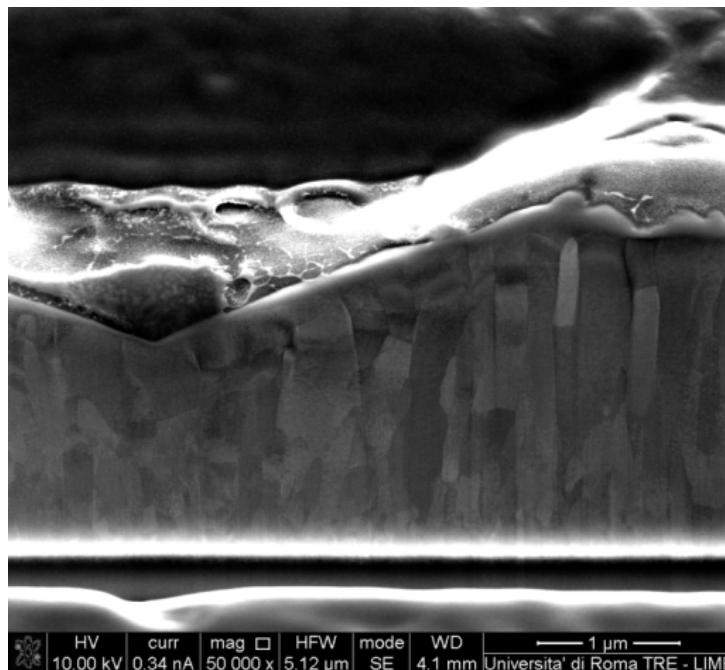
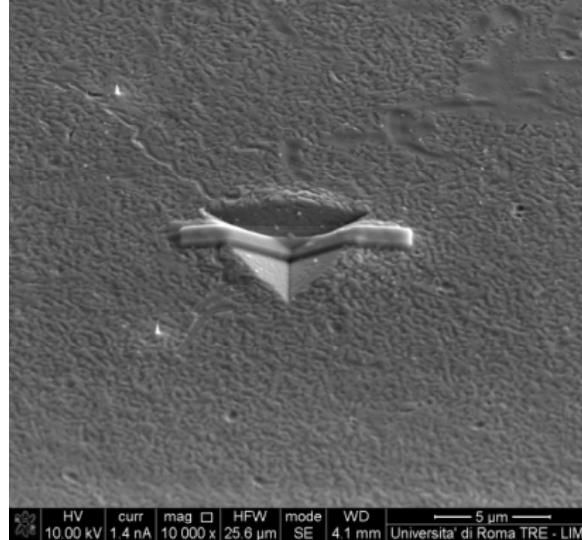
# NANOINDENTATION ON Nb THIN FILMS

- Pt deposition and FIB sectioning



500 nm

Partial re-crystallization during plastic deformation;  
Relative sliding of columnar grain

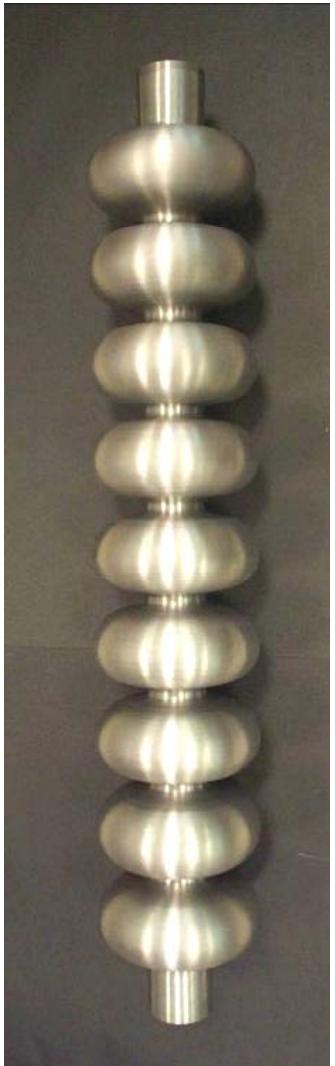


Direct measurement of piling-up  
Evaluation of the effects of roughness on contact area  
Analysis of deformation mechanisms

# CASE STUDY I

- Characterization of Nb superconductive coating through nano-mechanical testing and AFM-FIB / SEM-TEM analyses

# RESONANT CAVITIES FOR PARTICLE ACCELERATORS



## Bulk Niobium

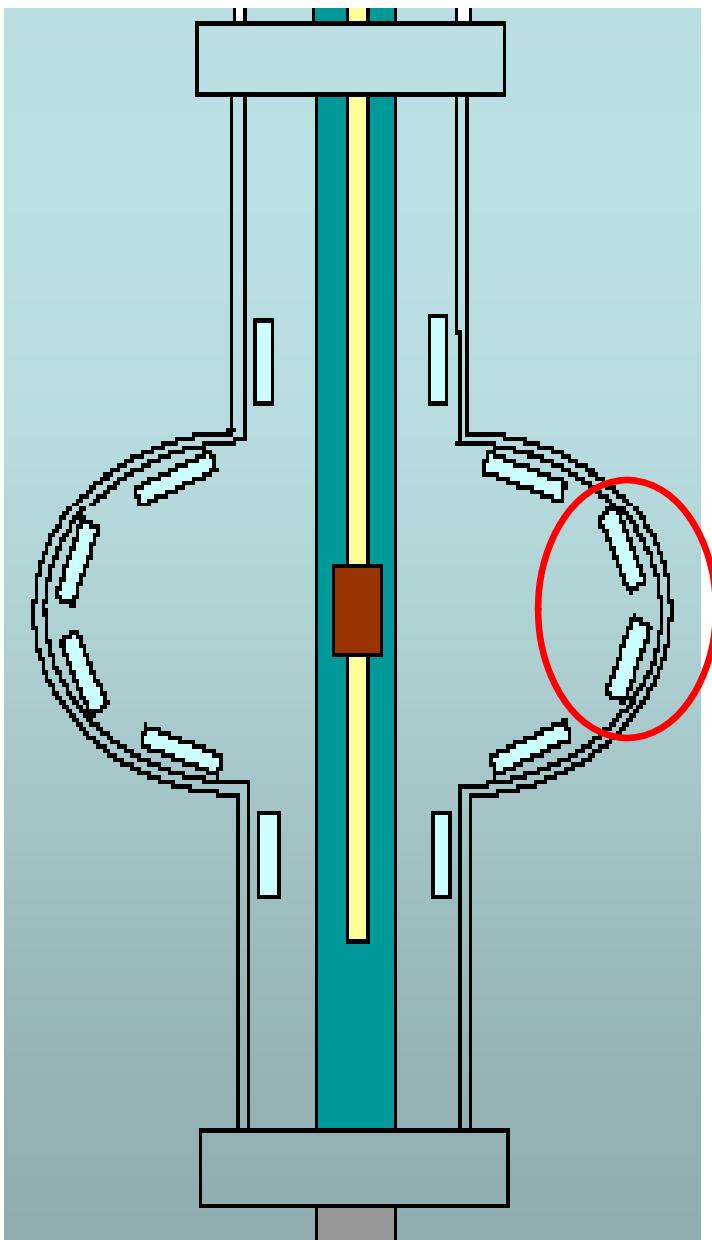
Very low  
Surface  
electrical  
resistance  
( $\sim n\Omega$  at 1,8 K)

## Niobium Coated (PVD) Copper cavity

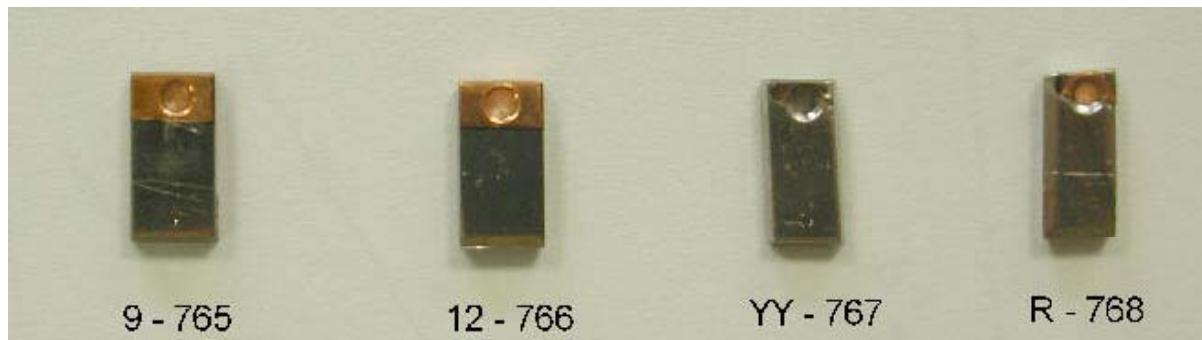


Lower costs  
Higher thermal stability  
But...  
**Significantly lower  
superconducting  
properties; WHY?**

## MATERIALS: COMPARISON OF TWO DEPOSITION PROCEDURES



9	765	CERN type sputtering
12	766	CERN type sputtering
YY	767	BIAS type sputtering (100V)
R	768	BIAS type sputtering (100V)

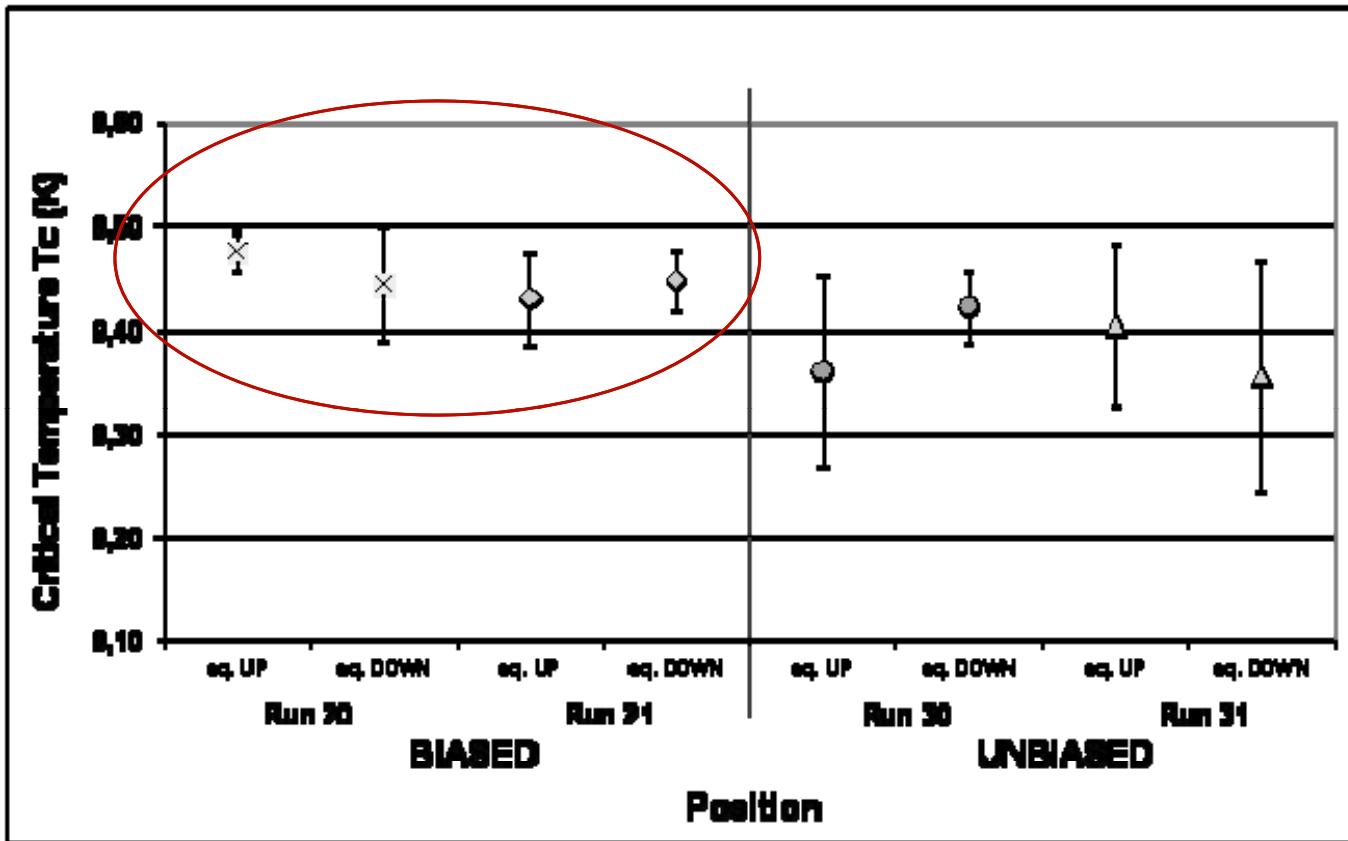


- Same coatings both on Copper and Quartz substrate.

# RESONANT CAVITIES FOR PARTICLE ACCELERATORS

- Quality control measurement (RRR and  $T_c$ )  
are usually performed on Nb film deposited on Quartz substrate
  - Even if useful as threshold parameters, RRR and  $T_c$  measured on Quartz, can lead to erroneous extrapolation for coatings deposited on copper substrate

## MICROSTRUCTURE TO FUNCTIONAL PROPERTIES: CRITICAL TEMPERATURE



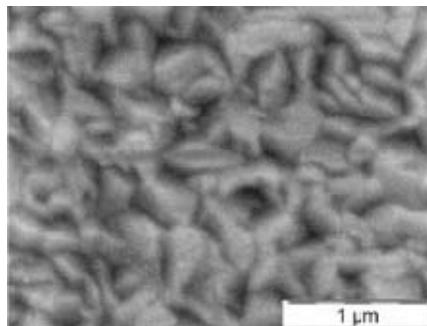
A critical temperature of 9,5 K is very unusual

- This suggest that strong microstructural differences do exist for BIASED coatings (density, grain size, lattice distortion, residual stress, resputtering)

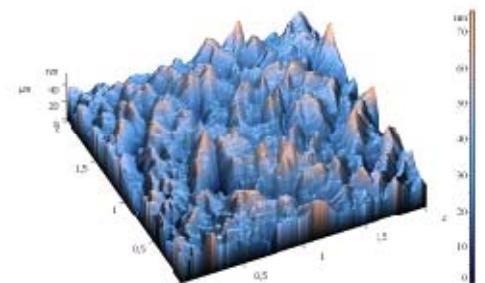
# COATINGS ON DIFFERENT SUBSTRATE

- Nb on **COPPER** substrate

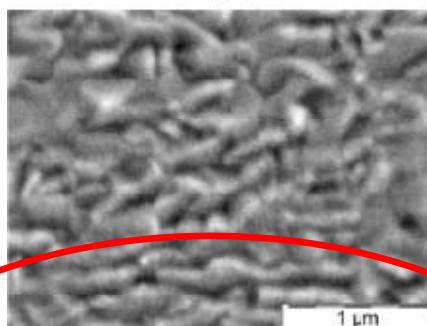
- BIASED (a-b)
- UNBIASED (c-d)



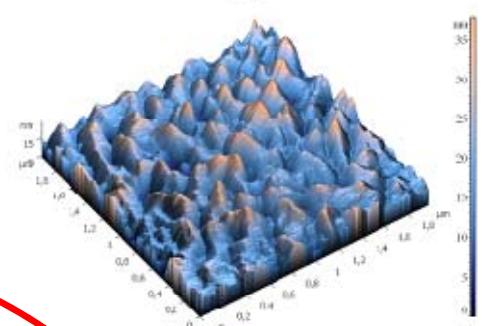
(a)



(b)



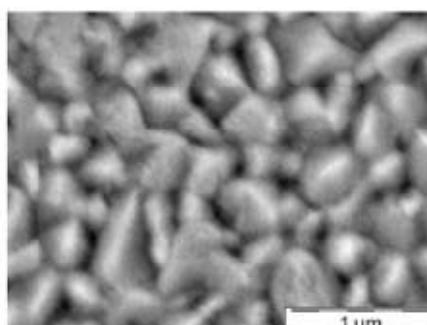
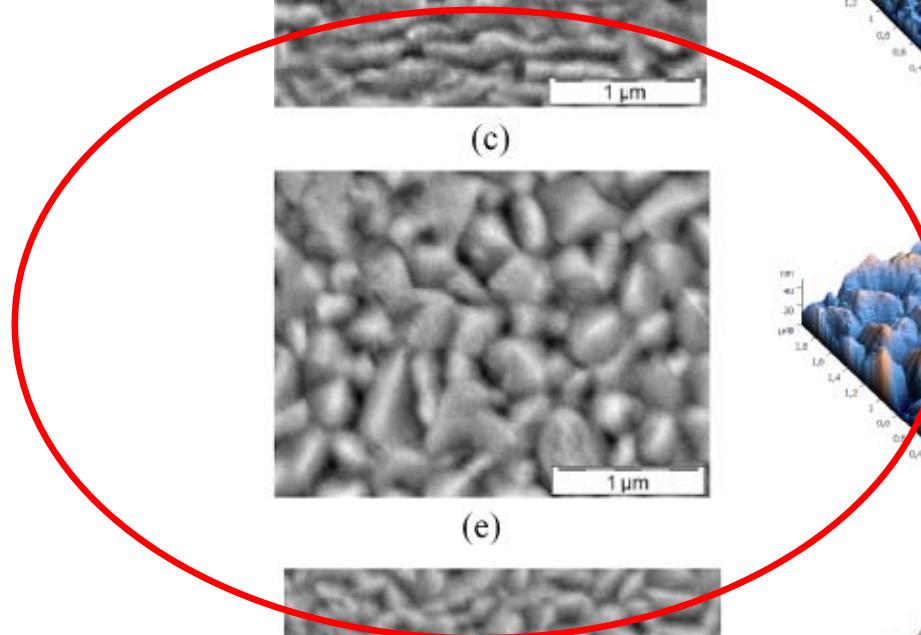
(c)



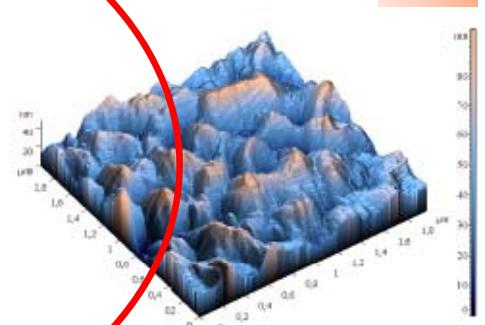
(d)

- Nb on **QUARTZ** substrate

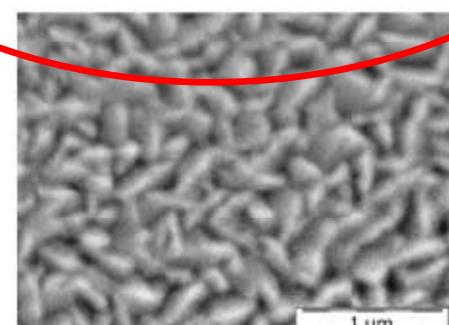
- BIASED (e-f)
- UNBIASED (g-h)



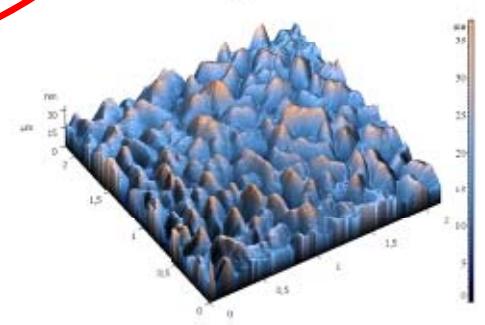
(e)



(f)



(g)



(h)

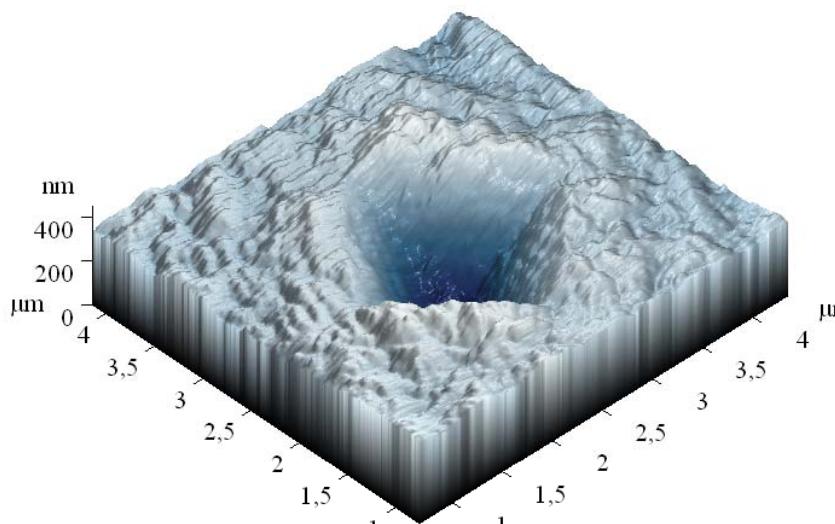
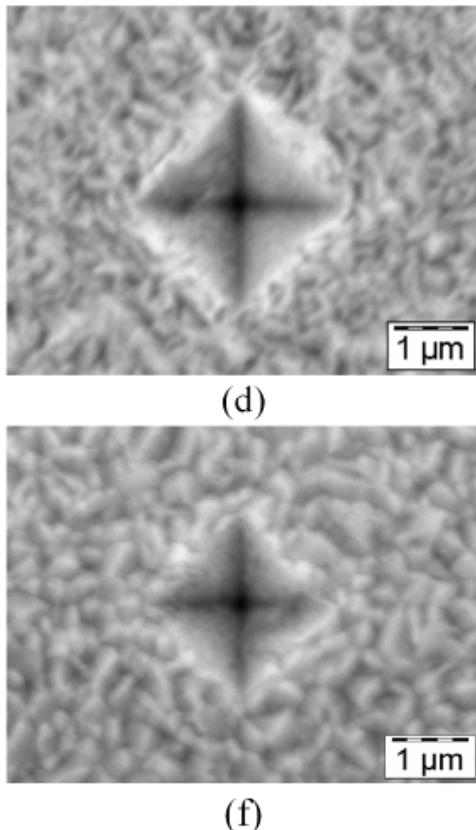
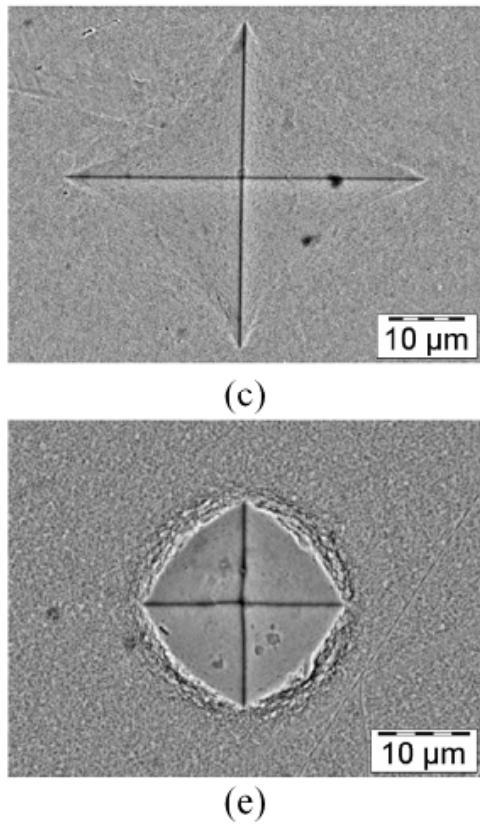
A different behaviour is expected for the BIASED Nb coating deposited on Quartz substrate

## CORRELATION OF MECHANICAL WITH FUNCTIONAL PROPERTIES

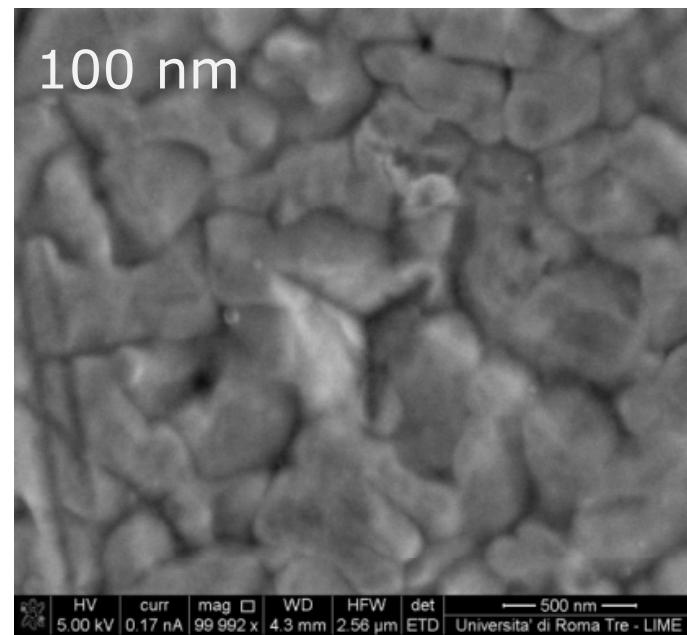
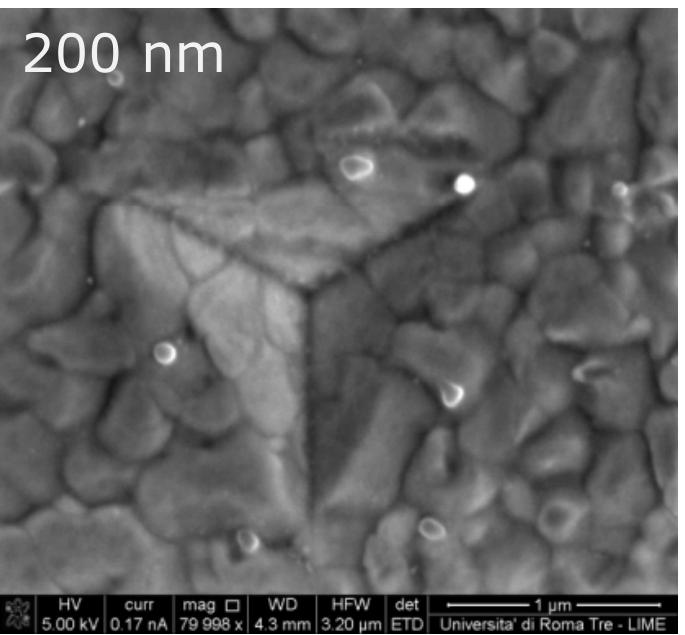
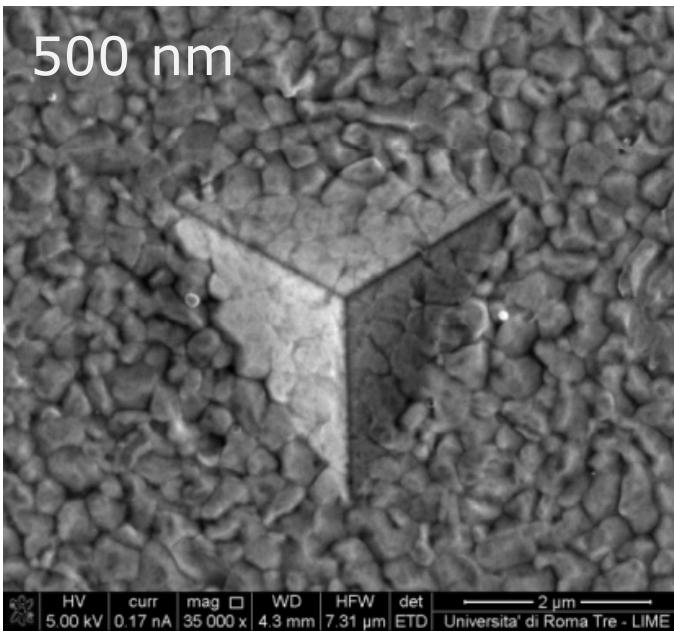
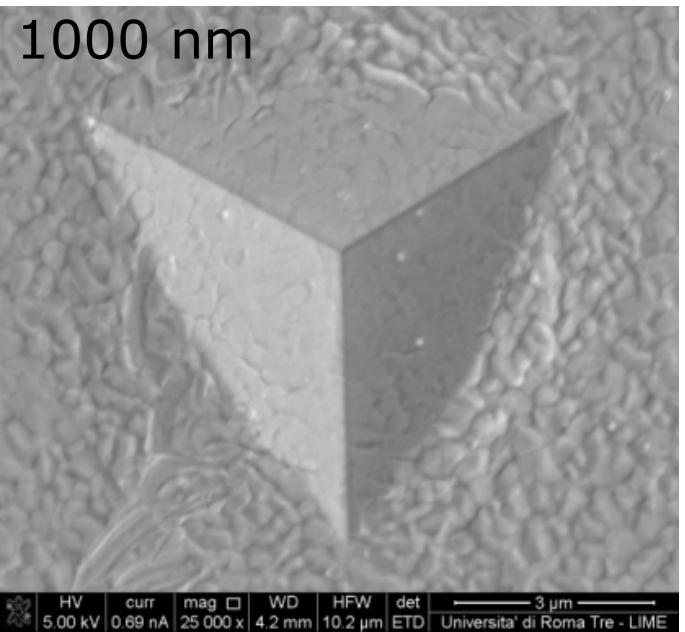
- Superconducting properties of MS-PVD Nb films are significantly affected by
  - Grain size
  - surface roughness
  - coating density
  - interfaces integrity
- So are Mechanical properties:

# HARDNESS MEASUREMENTS ON FUNCTIONAL COATINGS

- Can hardness testing (coupled with FIB-SEM validation) be useful for the prediction of functional performances of Nb thin films?



# NANOINDENTATION ON Nb THIN FILMS



# HARDNESS MEASUREMENTS ON FUNCTIONAL COATINGS

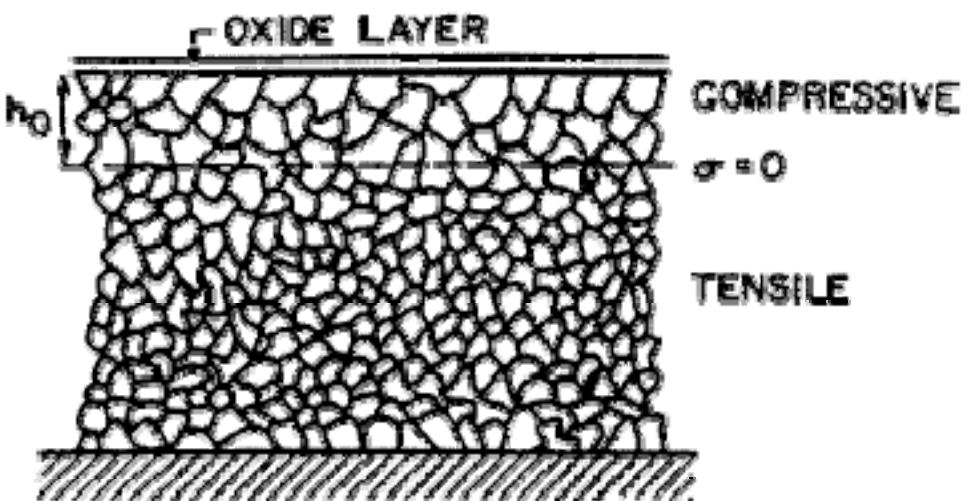
Sample code	Description	Nanoindentation		Standard micro-indentation
		H (GPa)	E (GPa)	H (GPa) Korsunsky model
796	Nb on Cu BIAS type	$3,10 \pm 0,58$	$101,5 \pm 23,61$	$2,51 \pm 0,15$
797	Nb on Quartz BIAS type	$1,63 \pm 0,30$	$76,22 \pm 48,99$	$1,75 \pm 0,12$
803	Nb on Cu CERN type	$2,59 \pm 0,35$	$108,68 \pm 11,65$	$2,38 \pm 0,15$
804	Nb on Quartz CERN type	$2,19 \pm 0,31$	$95,95 \pm 26,31$	$2,01 \pm 0,10$

# OXIDE LAYER CHECK

Halbritter, Journal Of  
Applied Physics **97**,  
083904 (April, 2005)



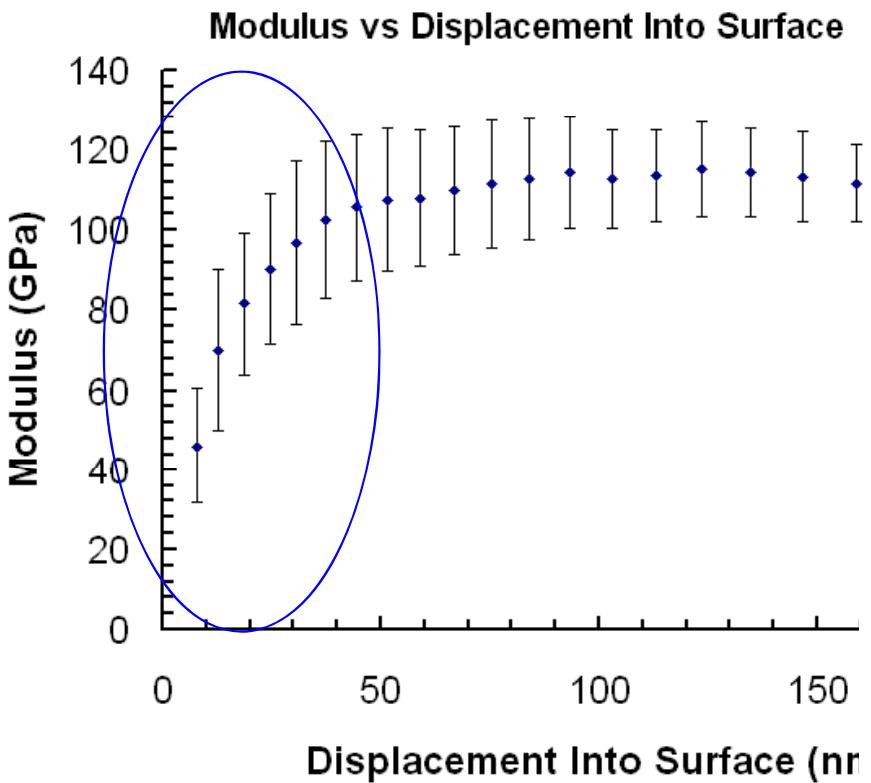
(a) VERY THIN FILM



(b) THICK FILM

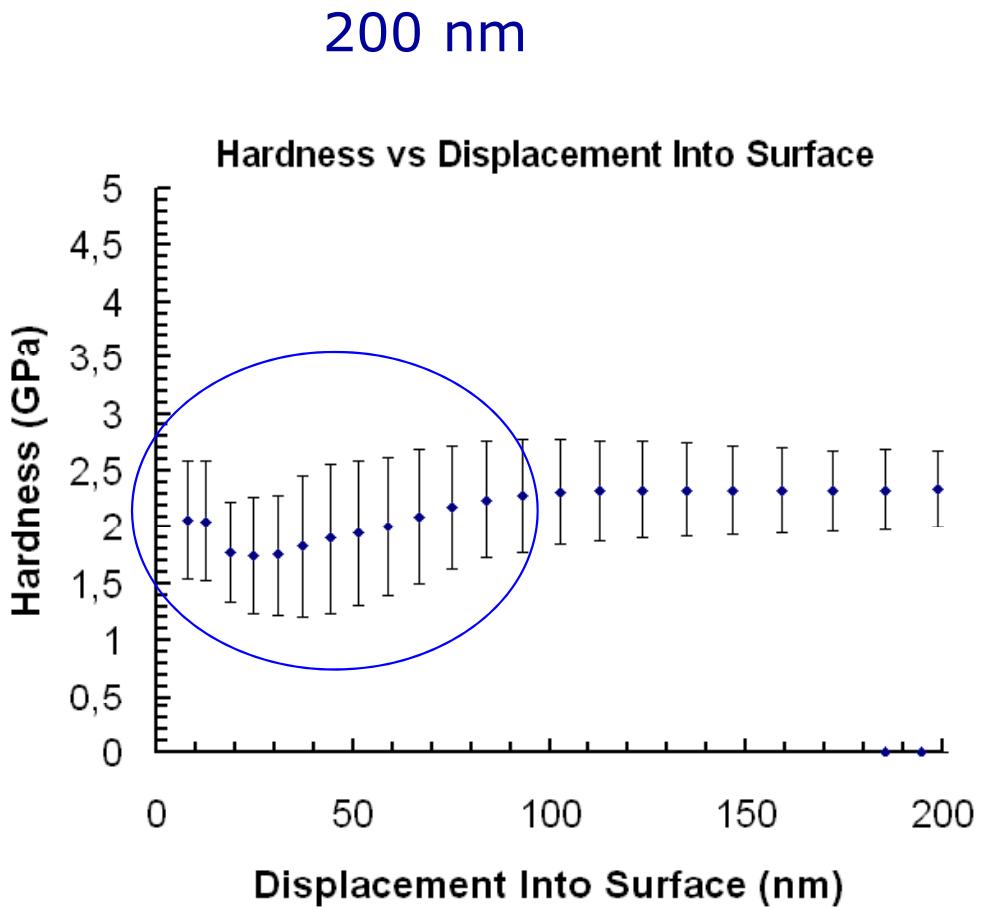
FIG. 1. Schematic cross section<sup>[15]</sup> of Nb/substrate composite: (a) Nb film oxidized along columns/grain boundaries. (b) Thick Nb film with compressed Nb layer by oxidation along the columns up to a depth of about  $W=0.01-3\ \mu\text{m}$  removing H<sub>2</sub> out of the interface layers. Below the surface layer column/grains are under tensile stress depending on sputter condition and on implanted sputter gas.

# NANOINDENTATION (CSM) ON Nb THIN FILMS

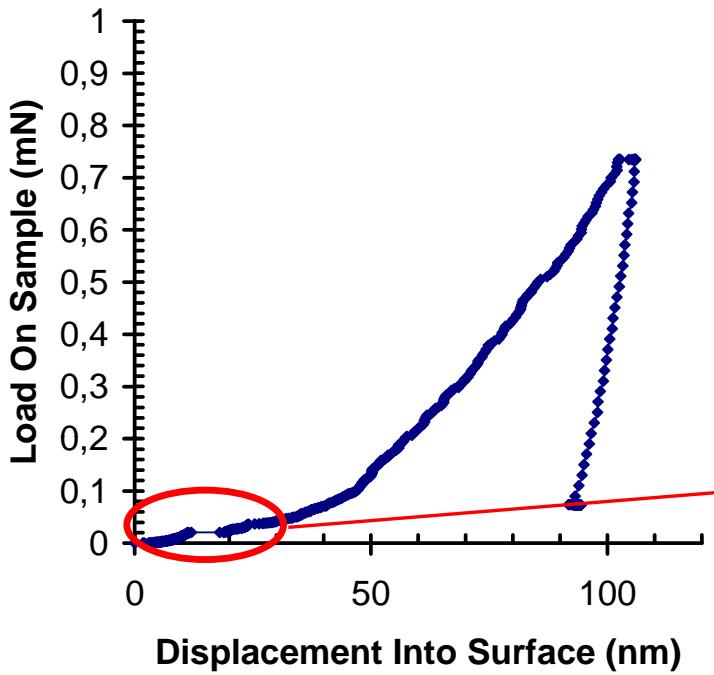


Elastic modulus at 25 nm:  
 $94,1 \pm 22,27$  GPa

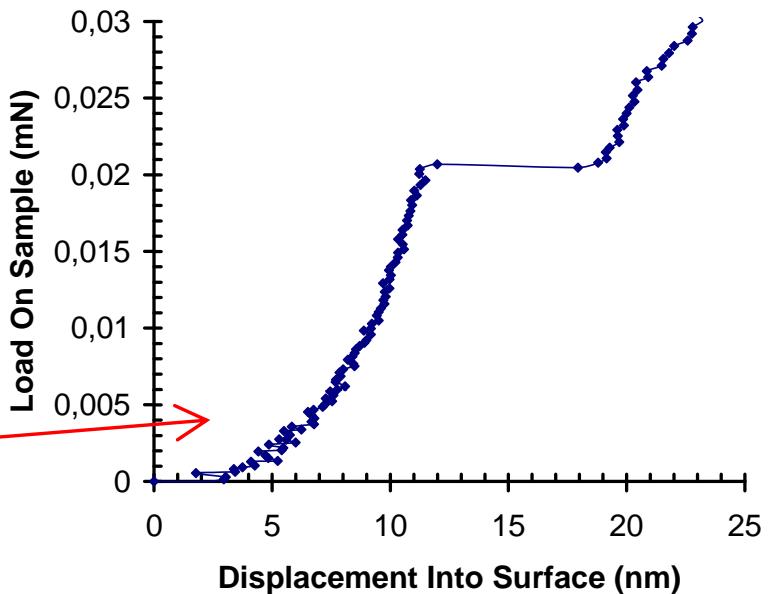
Elastic modulus at 100 nm:  
 $112,9 \pm 12,22$  GPa



# OXIDE LAYER CHECK VIA NANOINDENTATION



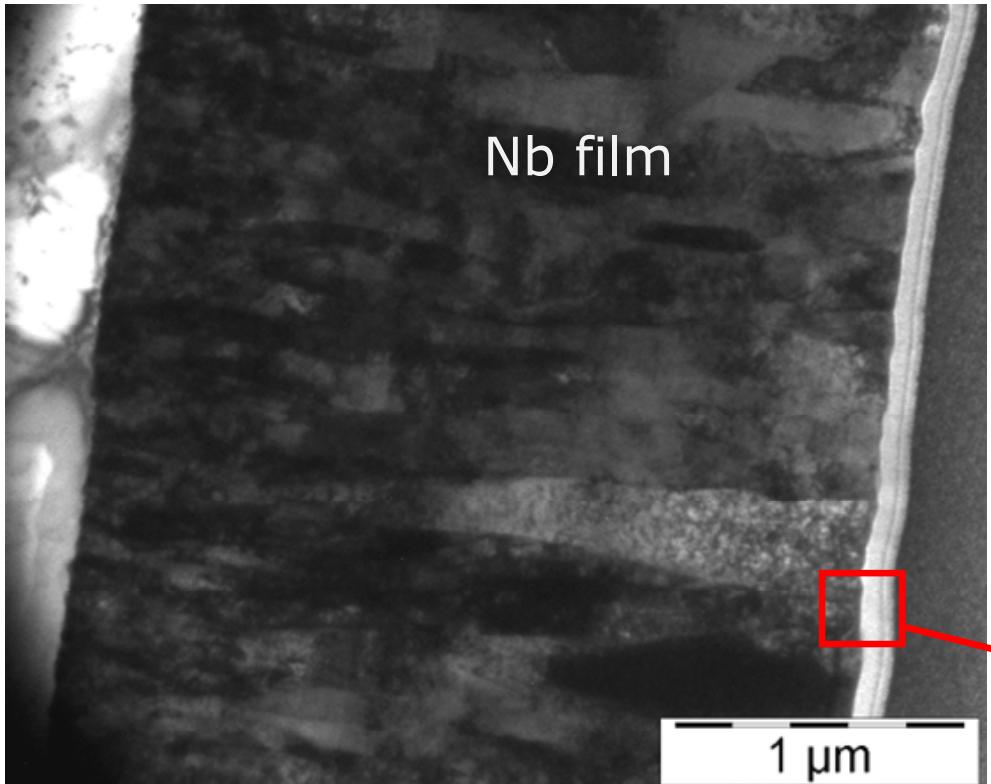
**Niobium film load-depth curve**



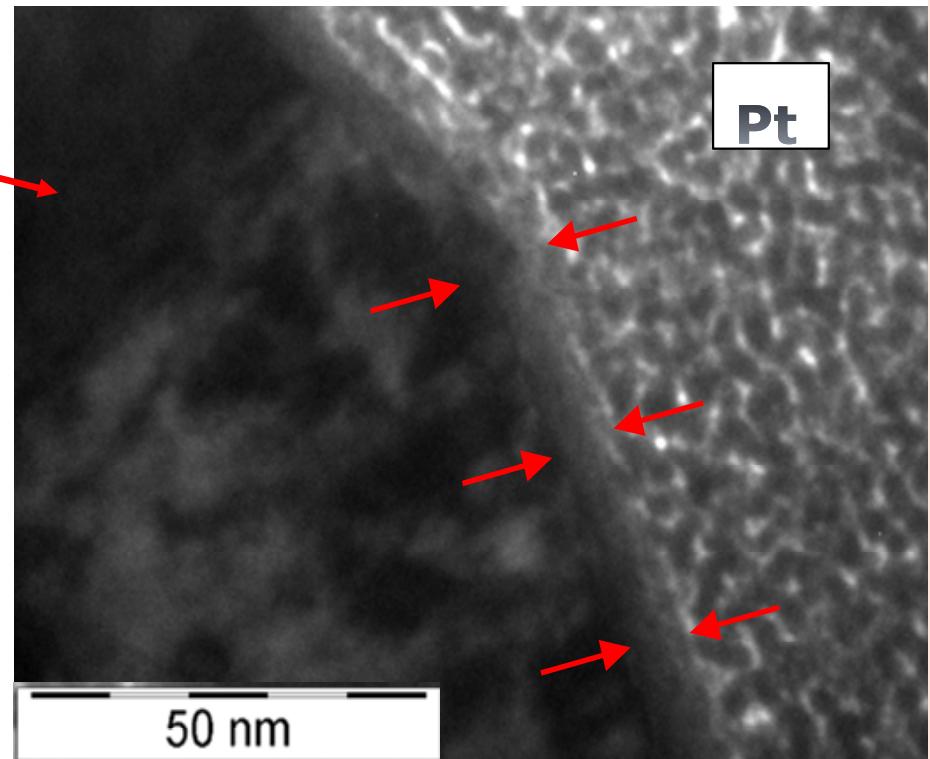
**Niobium film: Detail of a load-depth curve**

Indenter pop-in systematically at  $\sim$  10 nm depth

# TEM ANALYSIS OF THE OXIDE LAYER



TEM sample preparation by  
FIB lamella thinning



# CASE STUDY I: CONCLUSIONS

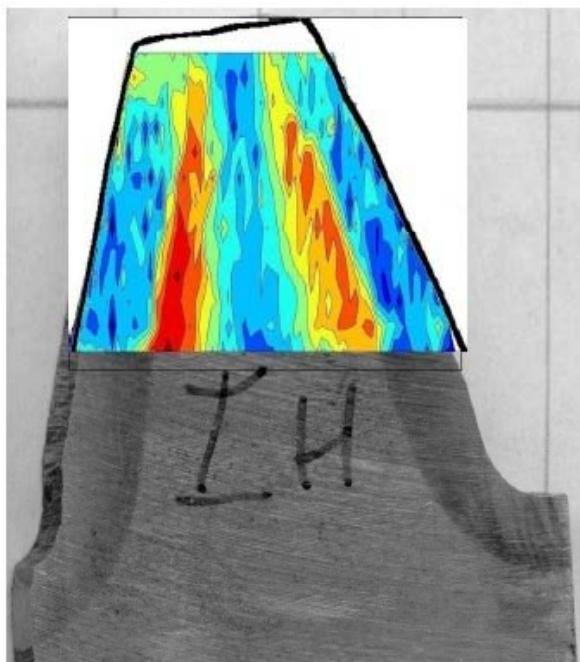
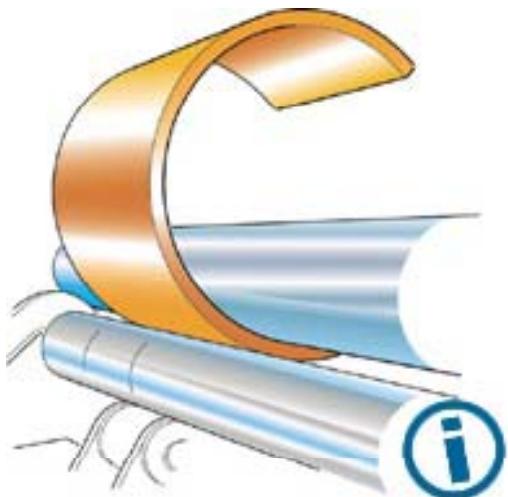
- In case of a soft-on-hard system, substrate can significantly affect the mechanical behavior of the coating;
- Different micro-structural effects and deformation mechanisms were observed at different applied loads
- Surface micro-roughness, coating density, and thickness of the surface oxide layers are strictly related to superconducting properties;
- The coupled use of microscopy techniques and hardness testing has been the key point of all research activities

# CASE STUDY II

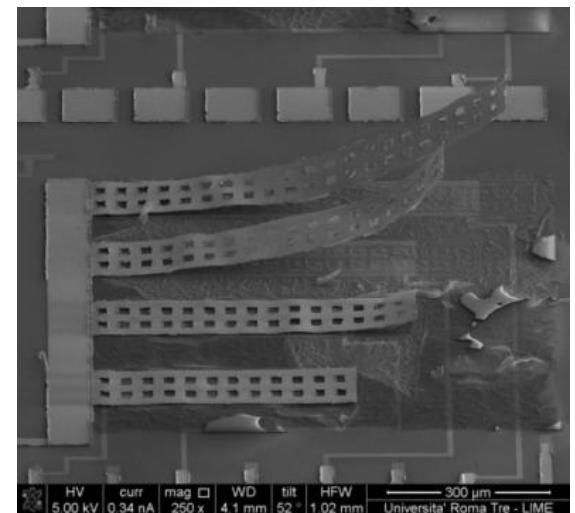
- **Residual Stress Evaluation at the Micrometre Scale: FIB Ring Drilling, Digital Image Correlation and Nanoindentation**

# INTRODUCTION

- **Residual stresses (RS)** play a crucial role in determining the deformation behaviour and performance of engineered components and materials at any scale;
- They come from unreleased (inelastic) deformation that remain after external forces has been removed.

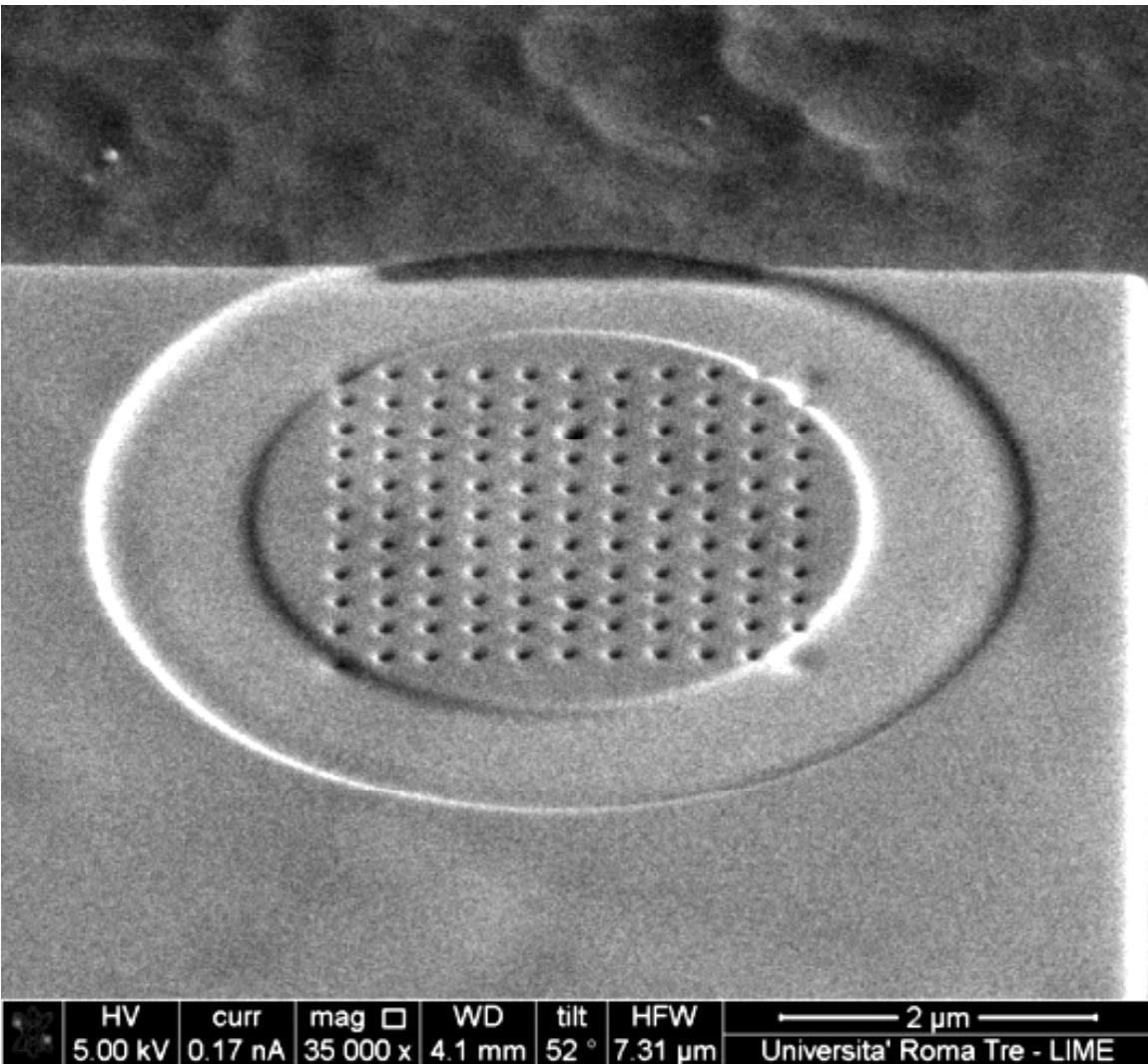


Gear tooth



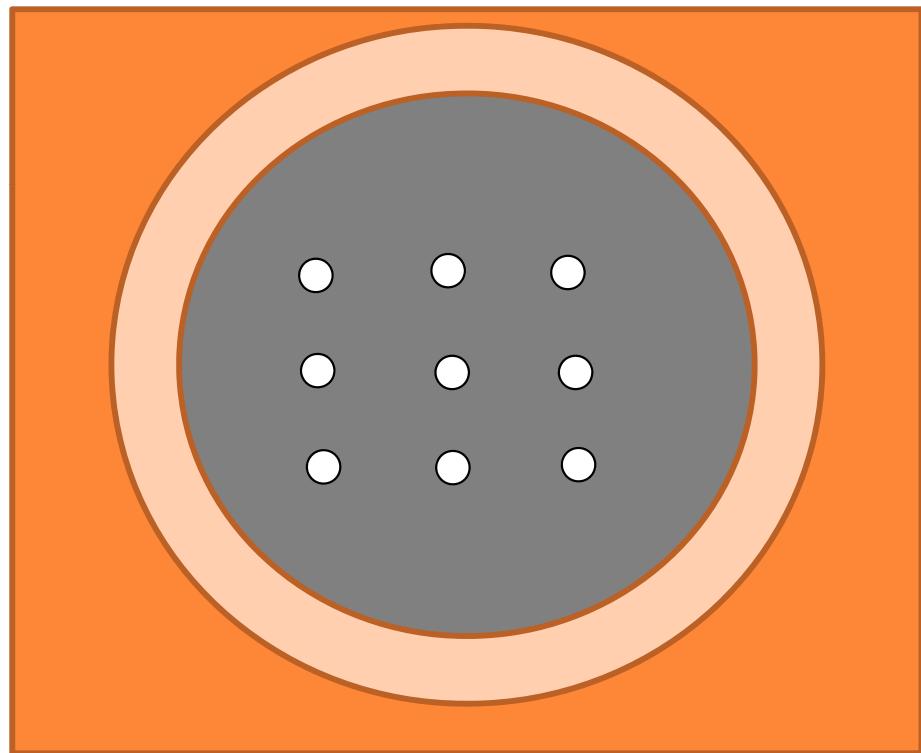
# FIRST METHOD, USING IMAGING CORRELATION:

1. Deposition of a Pt slice and milling of a reference dot pattern.

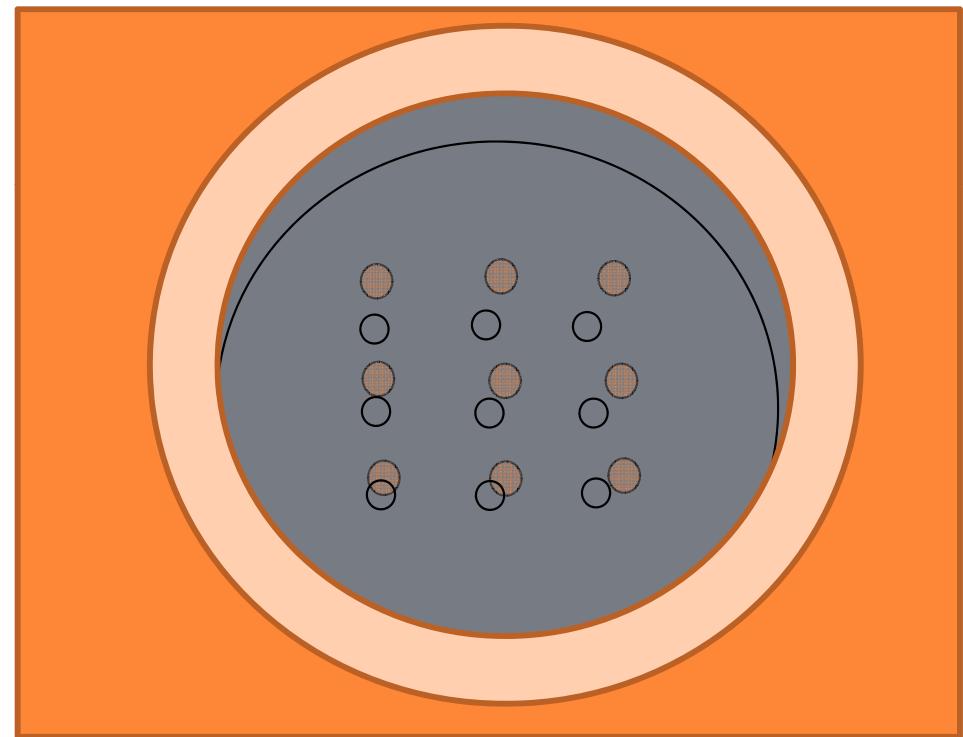


## FIRST METHOD, USING IMAGING CORRELATION:

2. Measuring the holes displacement (in X, Y and 45°) used to calibrate the FEM model.



Before ring cutting



After ring cutting

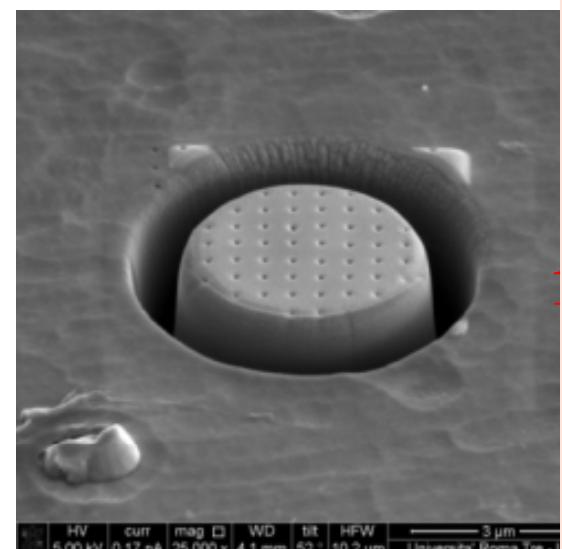
IN THIS WAY IS POSSIBLE TO MEASURE ALL IN-PLANE  
RELAXATION STRAIN COMPONENTS.

# RESULTS – ONE STEP MILLING

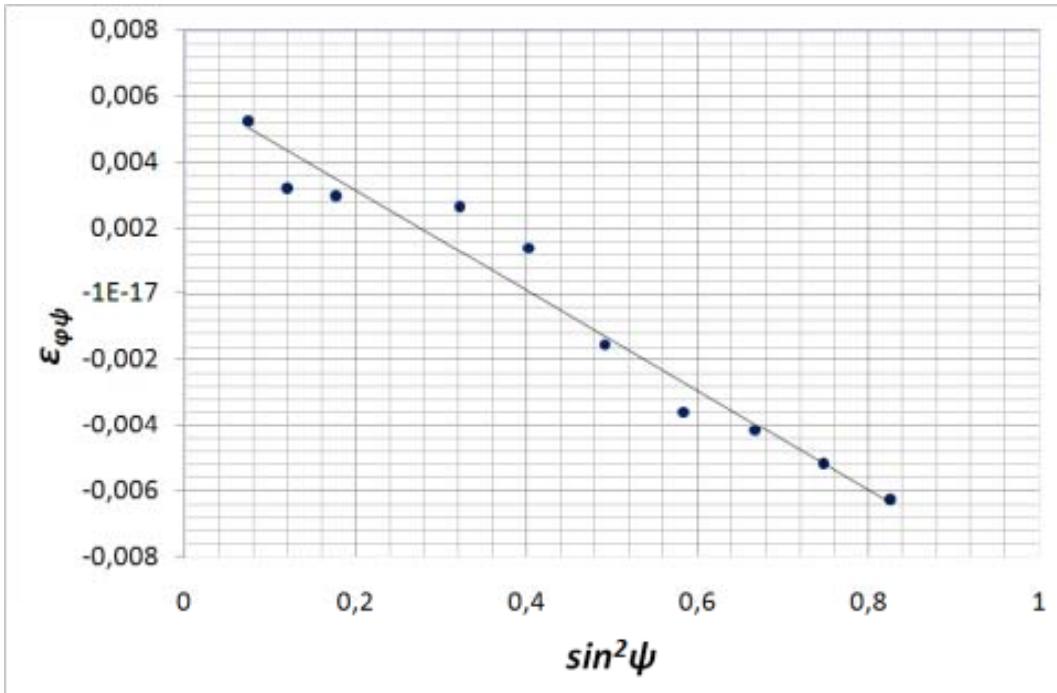
	Strain at maximum depth [um]	Calculated stress (FEM) [Pa]	Calculated stress (FEM) <b>Corrected with slope</b> [Pa]
Test-1	0.009	-6.00E+09	-5.96E+09
Test-2	0.0082	-5.47E+09	-5.35E+09
Test-3	0.009	-6.00E+09	-5.87E+09
Test-4	0.0097	-6.47E+09	-6.33E+09
Test-5	0.0103	-6.87E+09	-6.72E+09

- Analysis of the actual geometry of the pillar;
- The actual slope of the pillar is reproduced in the FEM model for **stress-strain** calibration

Calculated average stress: **-6.04 ± 0,51 GPa**

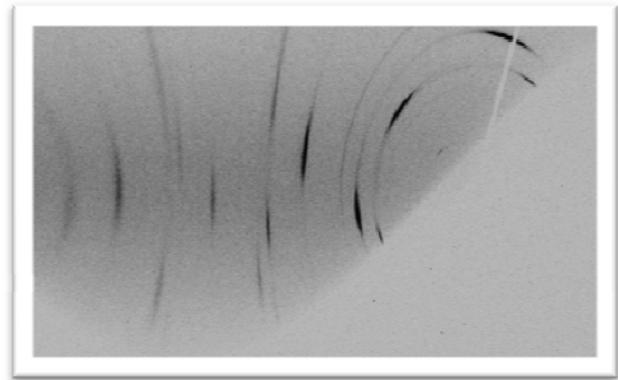


# METHOD VALIDATION Vs XRD-SIN<sup>2</sup>Ψ



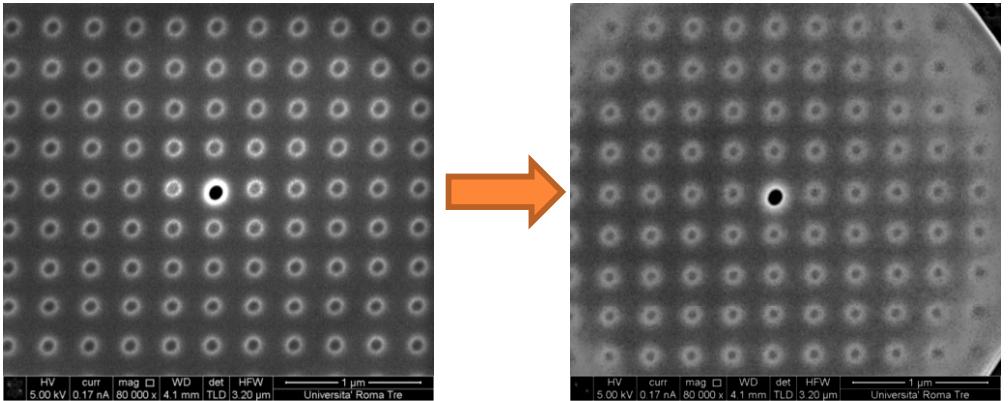
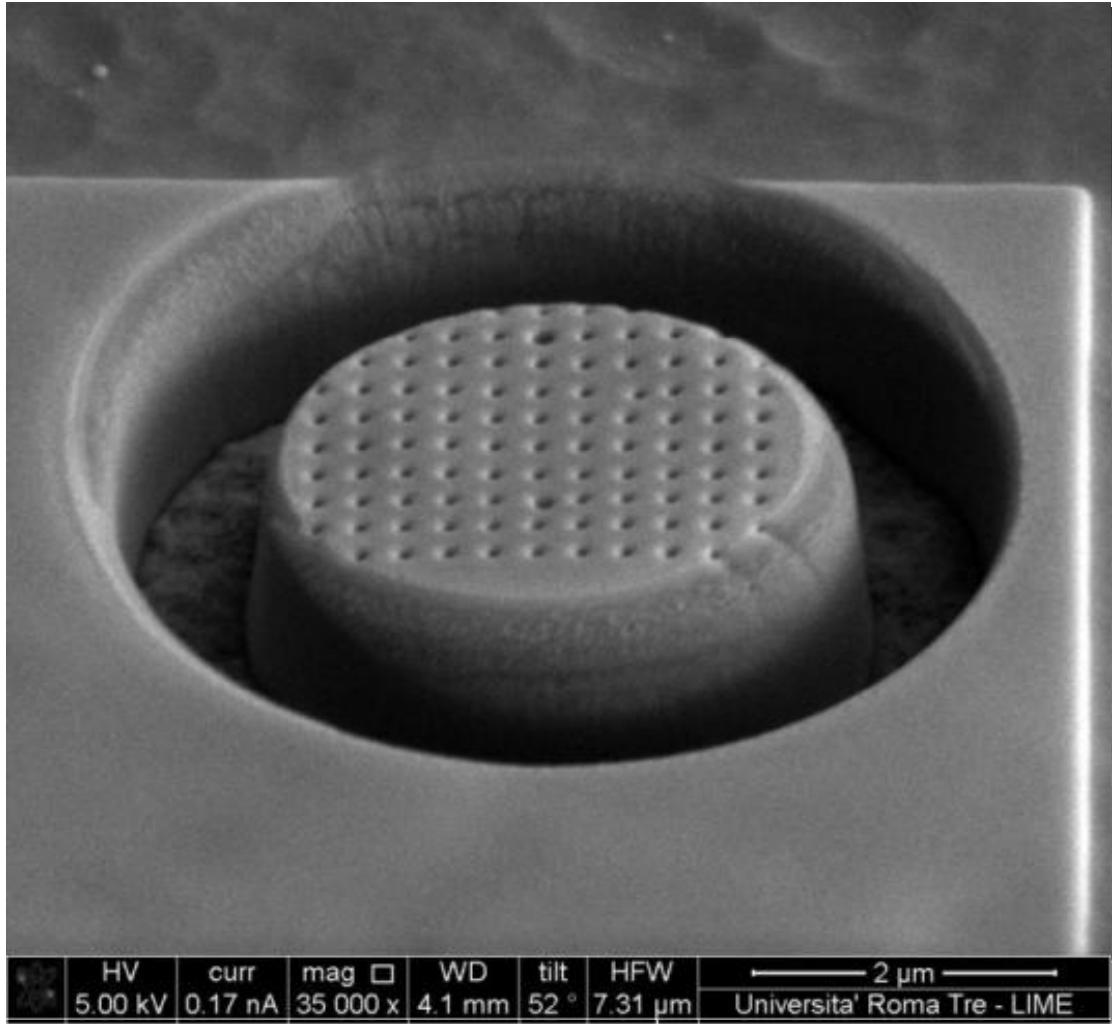
$$\epsilon_{\phi\psi} = \frac{1+\nu}{E} \sigma_\phi \sin^2\psi - \frac{\nu}{E} (\sigma_{11} + \sigma_{22})$$

$$\sigma_\phi = - 5.840 \text{ GPa}$$



- Data from XrD measurement not easily readable due to a strong texturing of the TiN coating;
- Nevertheless, obtained values are comparable with FIB obtained values

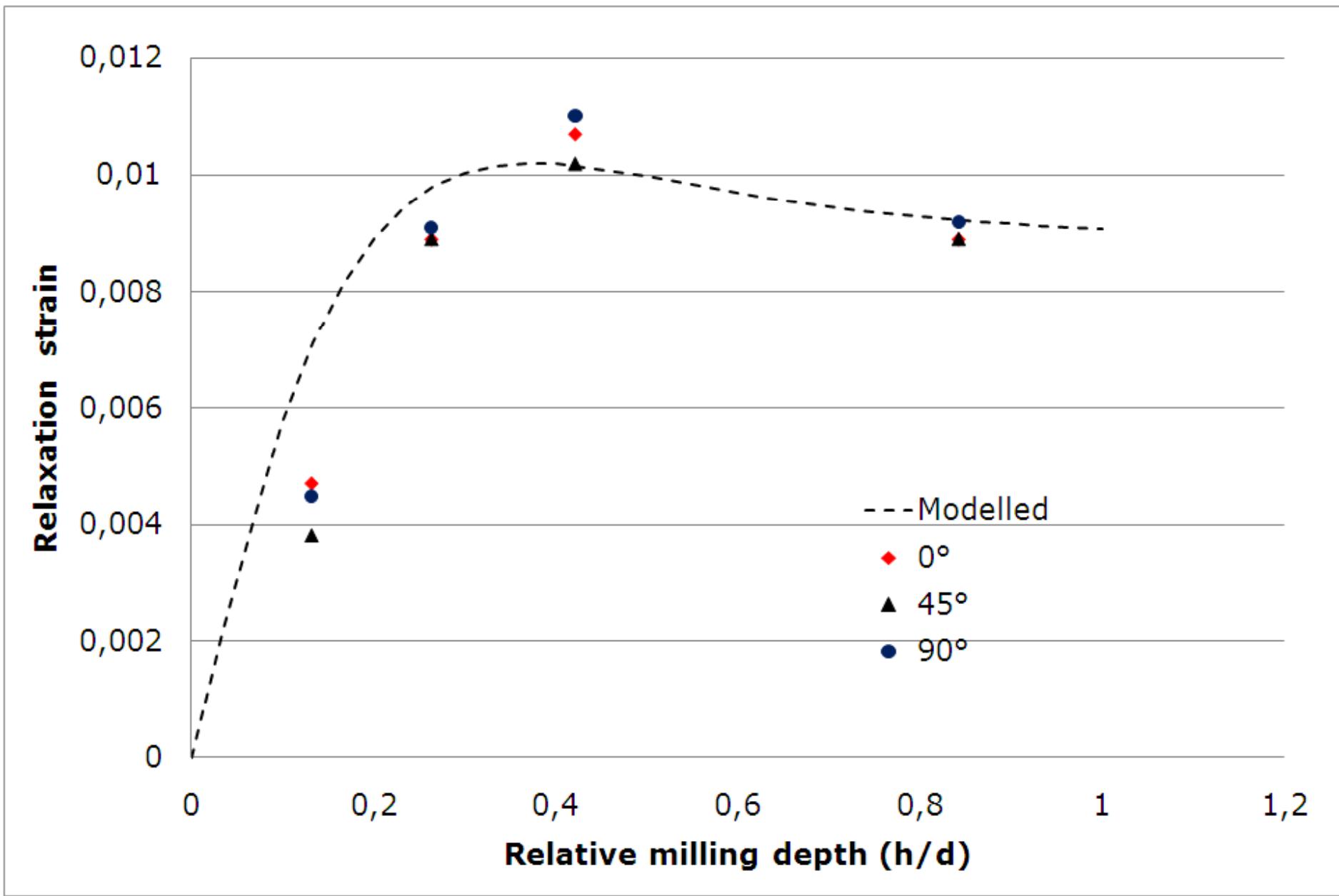
# PROCEDURE DETAILS



$Z=0$  vs each step

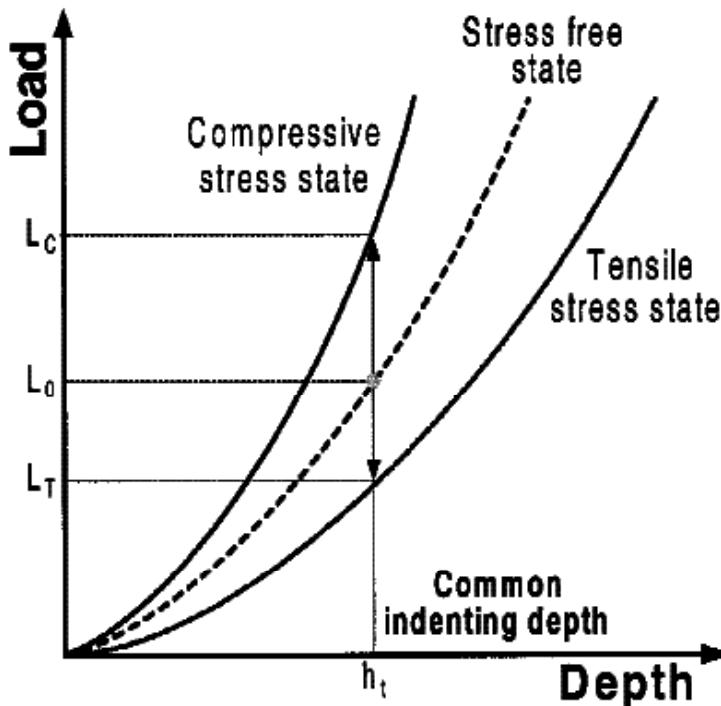
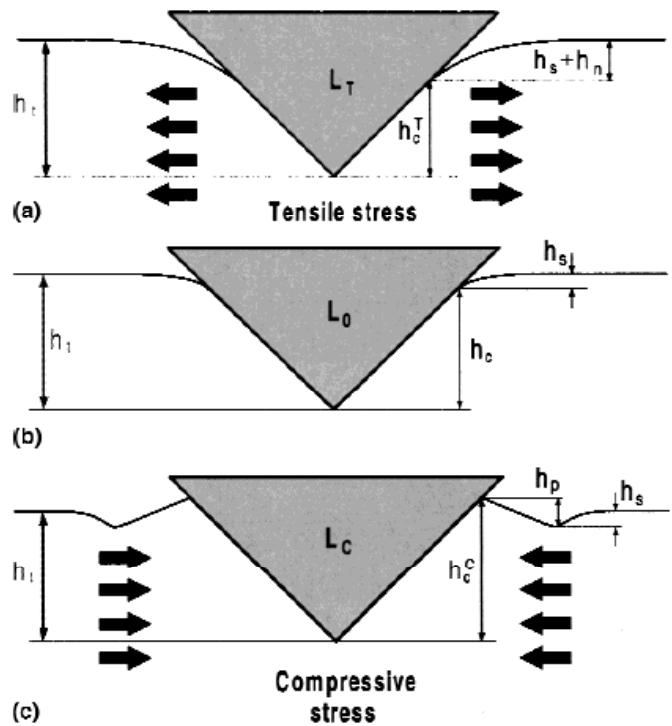
- Incremental Milling;
- Steps of 200 nm
- The pillar size  $d$  is equal to the coating thickness
- The maximum milling depth is equal to the coating thickness (3.8 μm)

# EXPERIMENTAL DATA

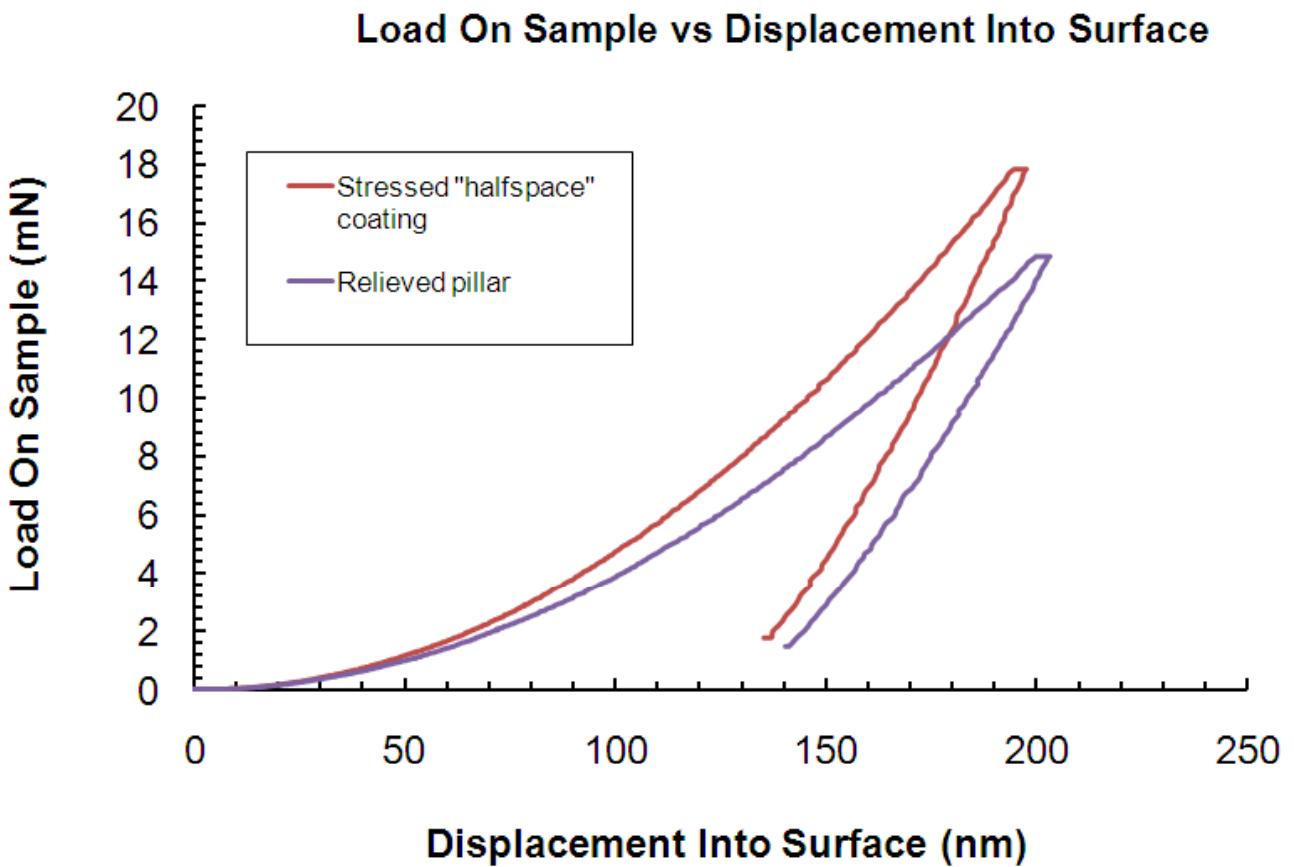


## SECOND METHOD, USING NANOINDENTATION:

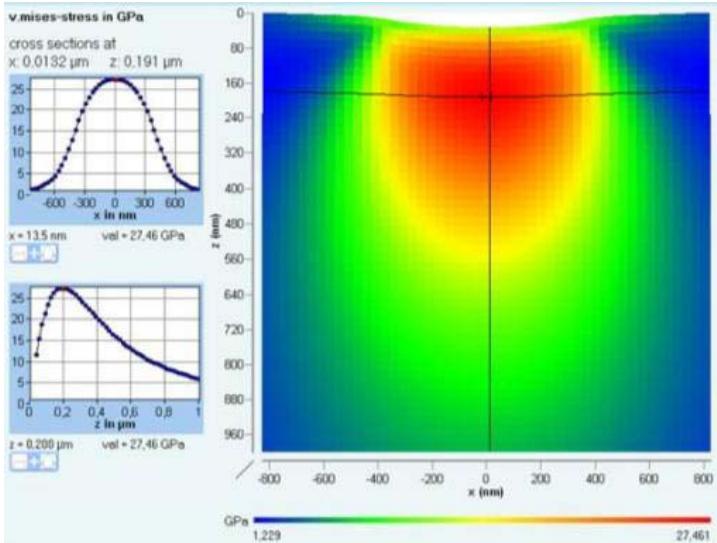
- A difference in the shape of the load-depth curve is therefore directly correlated to the presence of a biaxial residual stress state, due to changes in the actual contact area during indentation.



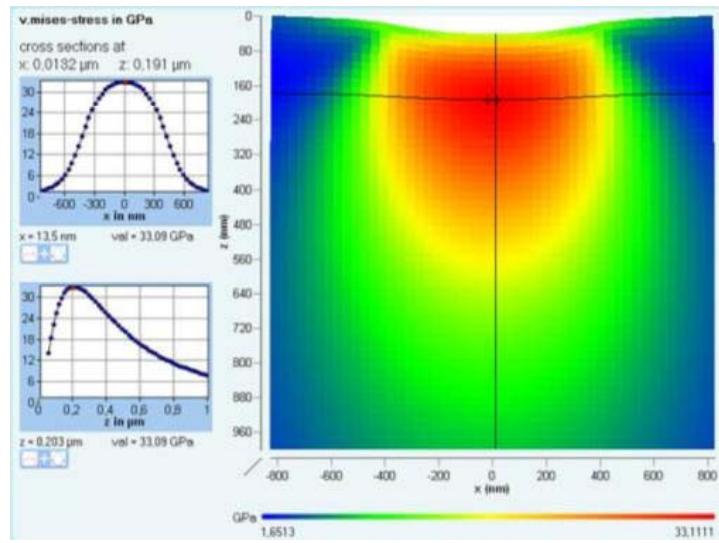
## SECOND METHOD, USING NANOINDENTATION:



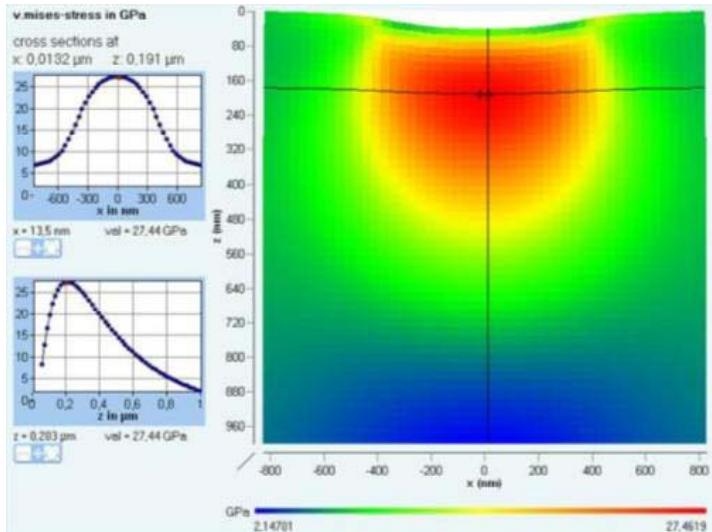
# RESULTS – STRESS CALCULATIONS



a) Pillar – stress free – as measured



b) Halfspace stressed coating – as measured



c) Modelled: Halfspace coating + RS

- Evaluation the contact stress field in the moment of unloading for both stressed surface and stress relieved pillar.
- In this way, a residual stress stat of – 5,653 Gpa was evaluated by comparison of the two set of load-depth data.

# CONCLUSIONS

- Research activities at LIME are focused on the development and application of high resolution, multi-technique, multi-scale procedures for the mechanical/micro-structural characterisation of surfaces.
- In case of non homogeneous materials and coatings, the use of nano-indentation techniques, even at very low indentation depths, can be useful for a quick detection of important micro-structural aspects
- By the combination of micro- and nano-hardness testing and SEM-TEM-FIB-AFM microscopy techniques, a comprehensive characterisation of nanostructured coatings and complex structures can be achieved.

# Possible contribution to Condensed Matter Nuclear Science, some ideas:

- Residual stress Measurements on Pd foils or tubes:

- Young's Modulus (E): 118-124 Gpa
- Poisson ratio ( $\nu$ ): 0.385-0.395
- Yield Stress (YS): 50-200 MPa (Pd bulk)

100 MPa residual stresses (0,5 YS), would led to  
0,05% relative relaxation  
( $\epsilon = \sigma * (1 - \nu) / E$ )

# Possible contribution to Condensed Matter Nuclear Science, some ideas:

- Surface and local mechanical properties (even inter-grain):
  - density gradients
  - real and apparent elastic modulus
  - Embrittlement phenomena

# Possible contribution to Condensed Matter Nuclear Science, some ideas:

- Site specific investigation on surface and subsurface:
  - micro/nano-structural changes (micro-cavities formation concerns)
  - Elemental analyses via FIB TEM of the very surface and interfaces at grain boundaries (gradients)
  - Electrodes decoration or patterning for a systematic study of roughness influence to micro-structural changes during the experiment
  - High aspect ratio patterning (i.e. pillar forest) to investigate surface vs. volume and fluido-dynamic effects during the experiment
  - More to your imagination...!

**THANK YOU FOR YOUR  
KIND ATTENTION**

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